

SUPPLEMENTARY INFORMATION

Spontaneous and self-oriented growth during chemical vapor epitaxy of single-crystalline MoS₂

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Note 1: MOCVD of MoS₂ from Mo(CO)₆ and H₂S

At the deposition temperature of 1000 °C, H₂S decomposes in the gas phase through the reversible reaction $\text{H}_2\text{S} \rightleftharpoons \text{H}_2 + \text{S}$ (Reaction 1).¹ H₂S and sulfur from the gas phase can adsorb on the surface, forming an S adatom. On the other hand, Mo(CO)₆ decomposes in the gas phase at the temperatures exceeding 250 °C, forming a Mo atom and carbonyl by-products.² Mo can react with H₂S (or S) in the gas phase, resulting in MoS₂. Alternatively, the generated Mo atom can adsorb on the surface, forming a Mo adatom. Both S and Mo adatoms can diffuse over the surface and aggregate with other adatoms to form nuclei or aggregate with already formed MoS₂ crystals. Sulfur adatoms can also desorb from the growth surface, diffuse in the gas phase, and adsorb again. In contrast, the desorption of Mo adatoms in this system has a low probability even at 1000 °C.³ As a result, the deposition proceeds in mass transport limited regime, and precursor delivery rate of Mo determines the metal adsorption and diffusion kinetics on the surface (**Figure 3b**). Due to the much higher concentration of supplied S compared to Mo precursor species, MoS₂ growth rate and nucleation density is primarily governed by the adsorption and diffusion kinetics of the metal ad-species (**Figure S2**).

The adsorption rate can be defined as $R_{\text{ads}} = S \cdot F$ (Reaction 2), where S is a sticking coefficient, and F is a precursor flux. For the Mo atoms adsorbing on the sapphire surface, the sticking coefficient can be considered a constant, ignoring adsorption on MoS₂ crystals in the initial growth stage. Then, the

adsorption rate of Mo atoms is determined by the flux of Mo atoms to the surface, which in turn is controlled by the metal concentration in the chamber. Thus, a higher Mo concentration in the gas phase leads to a higher adsorption rate, more Mo adatoms on the surface and, therefore, higher deposition rate, consistent with Figure 2a and b.

Following classical nucleation theory, higher partial pressure of the metal precursor leads to the lower potential barrier for the heterogeneous nucleation.⁴ Additionally, the higher metal concentration increases the probability of gas phase and surface aggregation, contributing to the higher areal density of MoS₂ crystals (Figure 3d). When Mo(CO)₆ concentration increases from 0.1 to 1.0 ppm, the maximal areal density of MoS₂ crystals also increases from 3.5·10² to 1.2·10³ crystals/μm², respectively. As a result, the interdomain distance between crystals in the steady state decreases from 56 to 29 nm when Mo(CO)₆ concentration increases from 0.1 to 1.0, respectively.

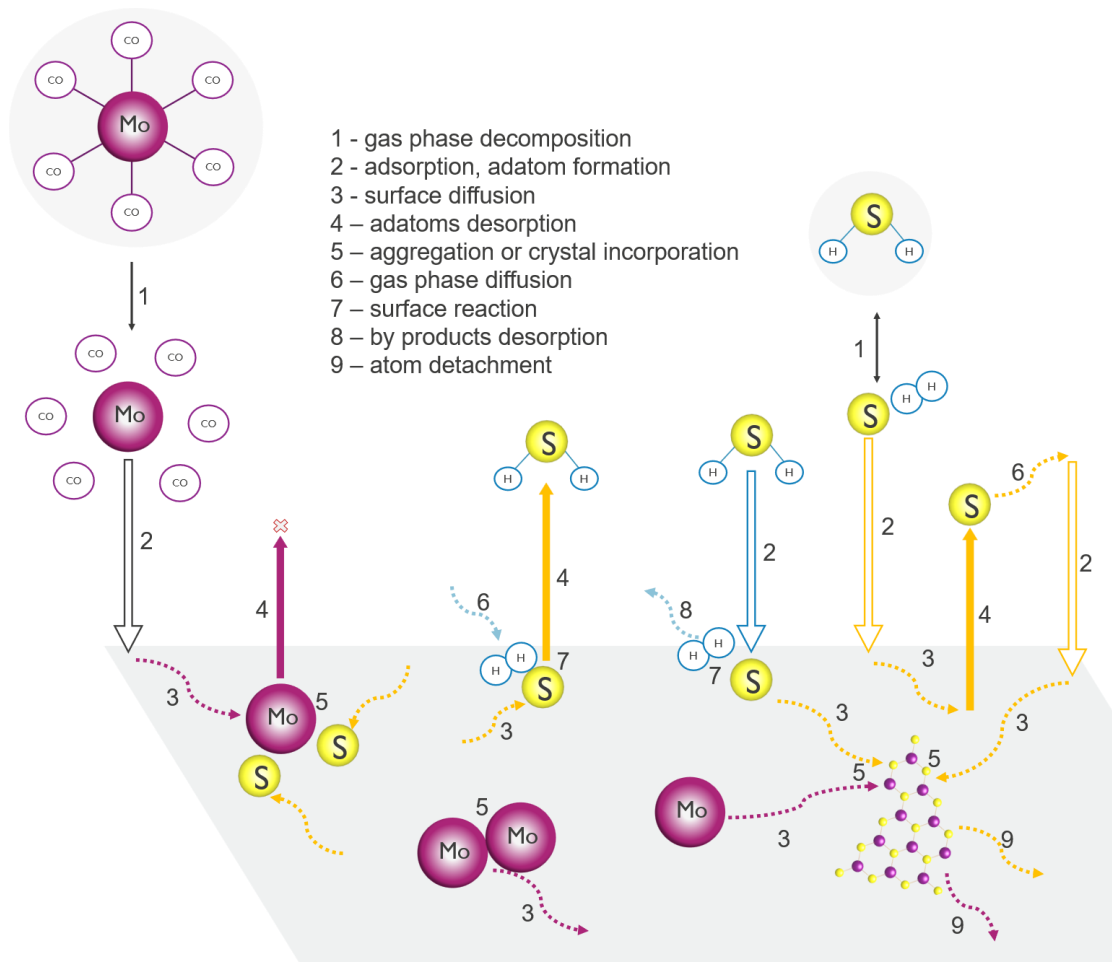


Figure S1. A schematic depicting the main processes occurring during MoS₂ CVD from Mo(CO)₆ and H₂S indicates the irreversible adsorption of Mo on the template's surface.

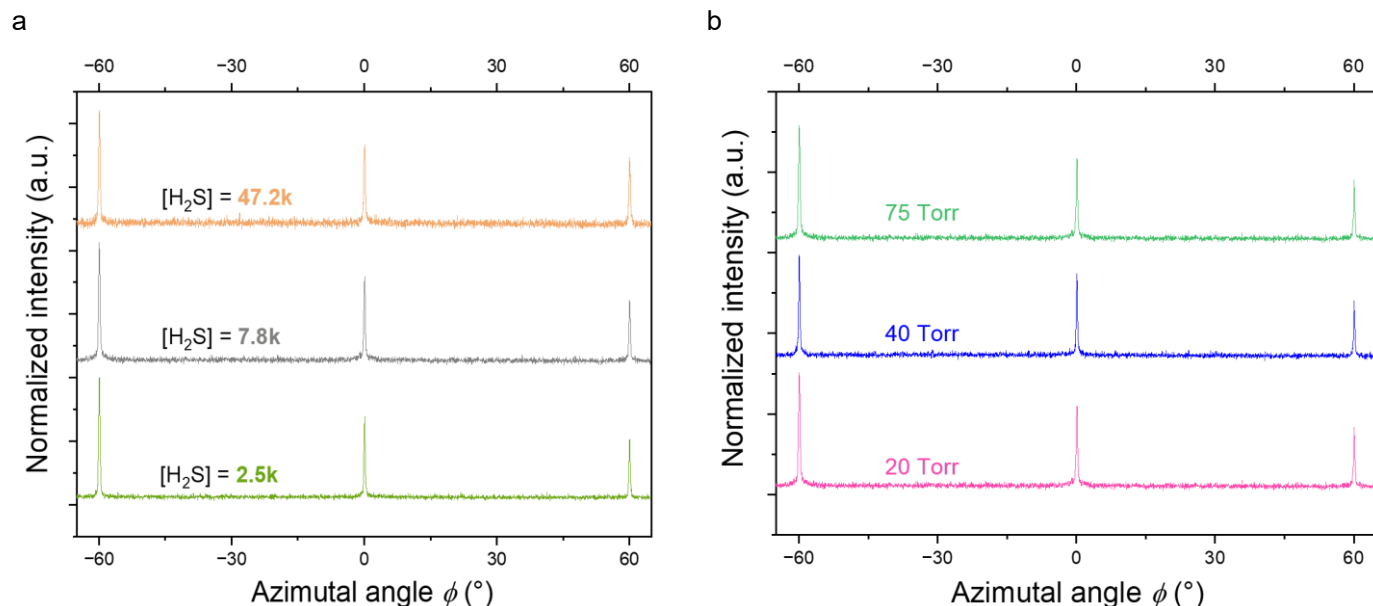


Figure S4. For MoS₂ crystals deposited with 0.6 ppm of Mo(CO)₆, we modify the total pressure in the chamber and the H₂S precursor concentration, keeping all the other process parameters the same. Changes in sulfur precursor concentration (a) and total pressure (b) do not affect the MoS₂ monolayer properties from an in-plane GI-XRD perspective.

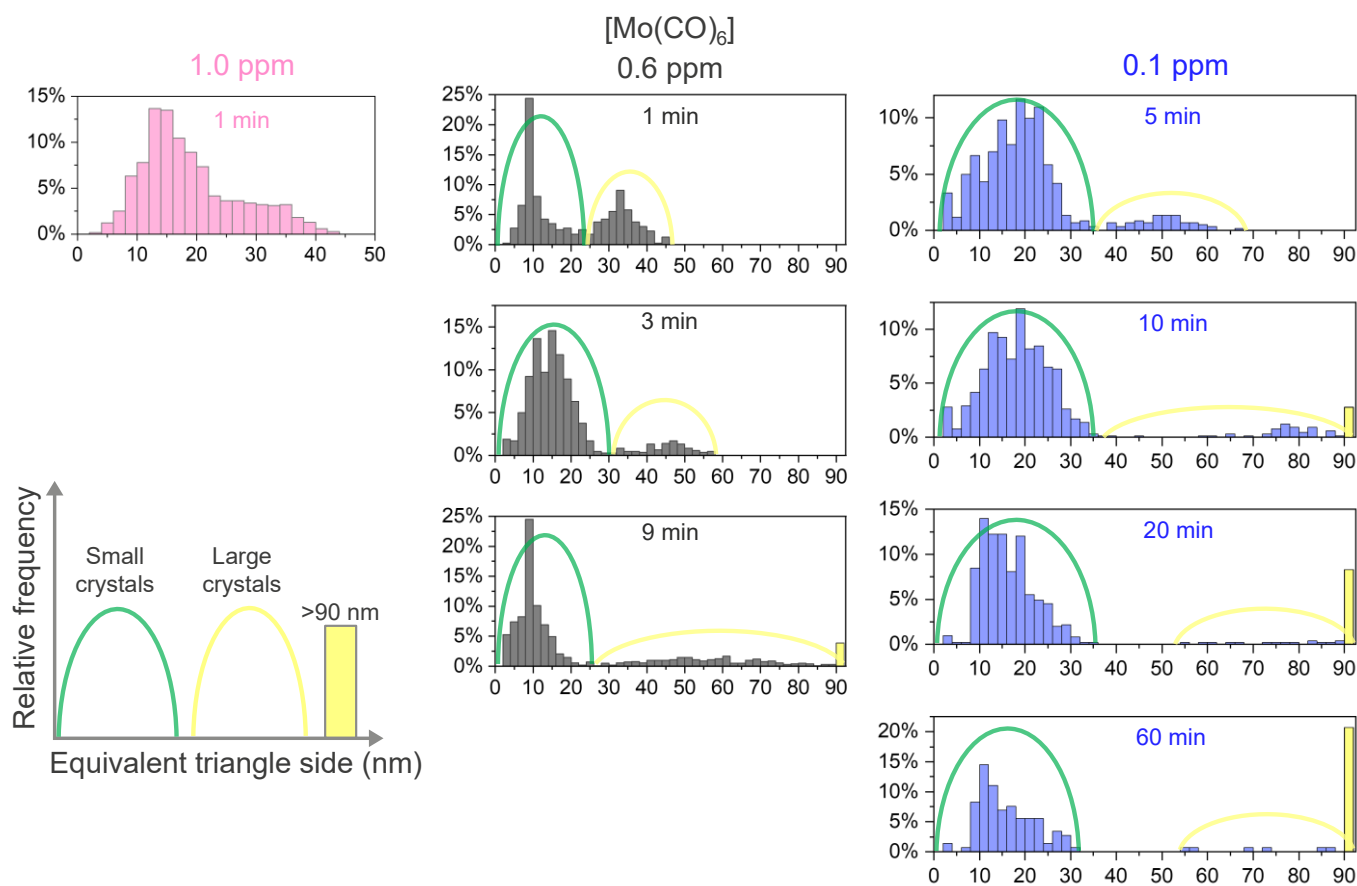
Note 2: Bimodal MoS₂ crystal size distribution

A non-uniform crystal size distribution is characteristic for the MoS₂ crystals. At a higher metal precursor molar concentration of 1.0 ppm, the MoS₂ crystals exhibit a high areal density and begin to coalesce quickly during the deposition process, making it difficult to study the evolution of crystal size. At lower metal precursor concentrations, the deposition process is slower, allowing the evolution of crystal size to be investigated (**Figure S5**). In the initial growth stage, two peaks in the crystal size distribution are present: the small crystals peak (S_{crystal}) and the large crystals peak (L_{crystal}). On one hand, the L_{crystal} peak shifts to the right during the deposition process, indicating a further increase in the size of large crystals. On the other hand, the S_{crystal} peak remains in the same position and does not change with deposition time. Interestingly, at the lowest metal precursor concentration of 0.1 ppm, where the growth of the MoS₂ domains is slow enough, a size gap between the large and small crystals is observed as deposition time increases. Thus, the small crystals on average do not grow beyond the critical size of 25-35 nm and are present throughout the deposition process.

The observed bimodality in MoS₂ crystallite sizes suggests three possible scenarios during crystal growth, depending on the relative kinetics of atom attachment, detachment, and adatom diffusion. In the first scenario, most of the stable nuclei form at the beginning of the deposition process, some grow faster,

81 forming the large crystals, while others remain small. In this case, the small crystals continuously attach,
 82 release and exchange atoms through a surface-mediated process with the larger crystals, contributing to
 83 their growth. Simultaneously, the small crystals do not exceed their critical size. In the second scenario,
 84 the small crystals undergo constant consumption by giving away all of their atoms and then regenerating
 85 (renucleation). Lastly in the third scenario, the small crystals are not present during the deposition process
 86 itself but form during the cooling down stage from Mo adatoms on the surface when the temperature
 87 begins to decrease, limiting the diffusion length of those adatoms. In all proposed scenarios, the large
 88 crystals are the main constitutive part of the MoS₂ monolayer, establishing its properties.

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91 **Figure S5.** The bimodal MoS₂ crystal size distribution during the deposition process for Mo(CO)₆ concentration of 0.6
 92 ppm and 0.1 ppm.

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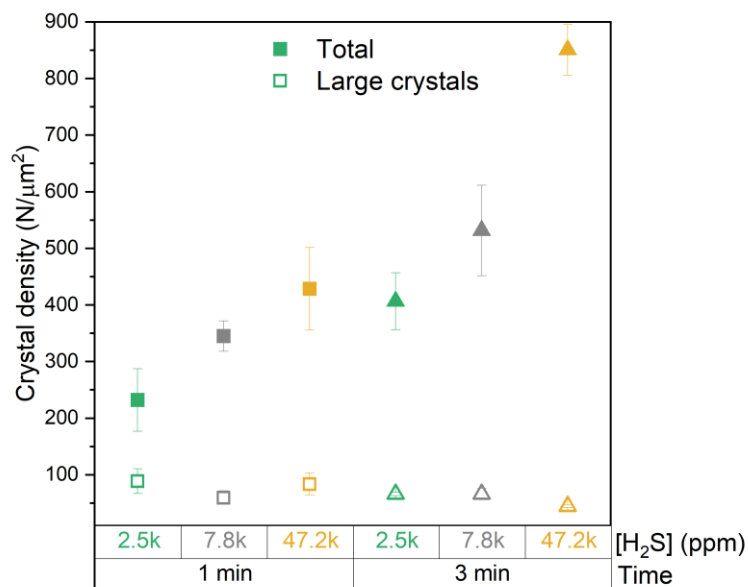


Figure S6. The MoS₂ crystal density increases early in the deposition process with the increase of the H₂S concentration, when deposited with 0.6 ppm of Mo(CO)₆. We hypothesize that interaction of H₂S/H₂ molecules with the sapphire substrate leads to surface defects formation. Around these surface defects, the nucleation probability of MoS₂ increases. However, the nucleation density increase is observed only for the small crystals, while the density of large crystals with an equivalent triangle side above 25-35 nm stays approximately the same. As the larger crystals dominate later in the deposition process, the closed MoS₂ monolayers free of misoriented domains, as confirmed by in plane GI-XRD (Figure S4).

I04 The ambient environment significantly influences the reconstruction behavior of the sapphire surface
I05 (**Figure S7a**). When the substrate is annealed in an inert nitrogen (N_2) or hydrogen (H_2) environment at
I06 1000°C for 30 minutes, only a slight change from the original surface morphology is observed. However,
I07 when annealing is performed in a hydrogen sulfide (H_2S) environment, a much more pronounced
I08 coalescence of terraces occurs, resulting in larger, more uniform surface areas. Interestingly, when the
I09 $Mo(CO)_6$ precursor is added to H_2S atmosphere during MOCVD and MoS_2 deposition is initiated, the
I10 sapphire surface modification proceeds differently compared to just the H_2S atmosphere. This indicates a
I11 coupled effect: on the one hand, the sapphire bulk crystallographic symmetry guides the MoS_2 orientation
I12 through van der Waals interactions, on the other hand, the growing MoS_2 crystals affects the way the
I13 sapphire surface reconstructs.

I14 On the other hand, the orientation of isolated MoS_2 crystallites remains unchanged when the sapphire
I15 surface is pre-annealed in H_2S , indicating that potential sulfur-induced surface passivation does not
I16 influence the epitaxial alignment of MoS_2 crystals (Figure S7b).

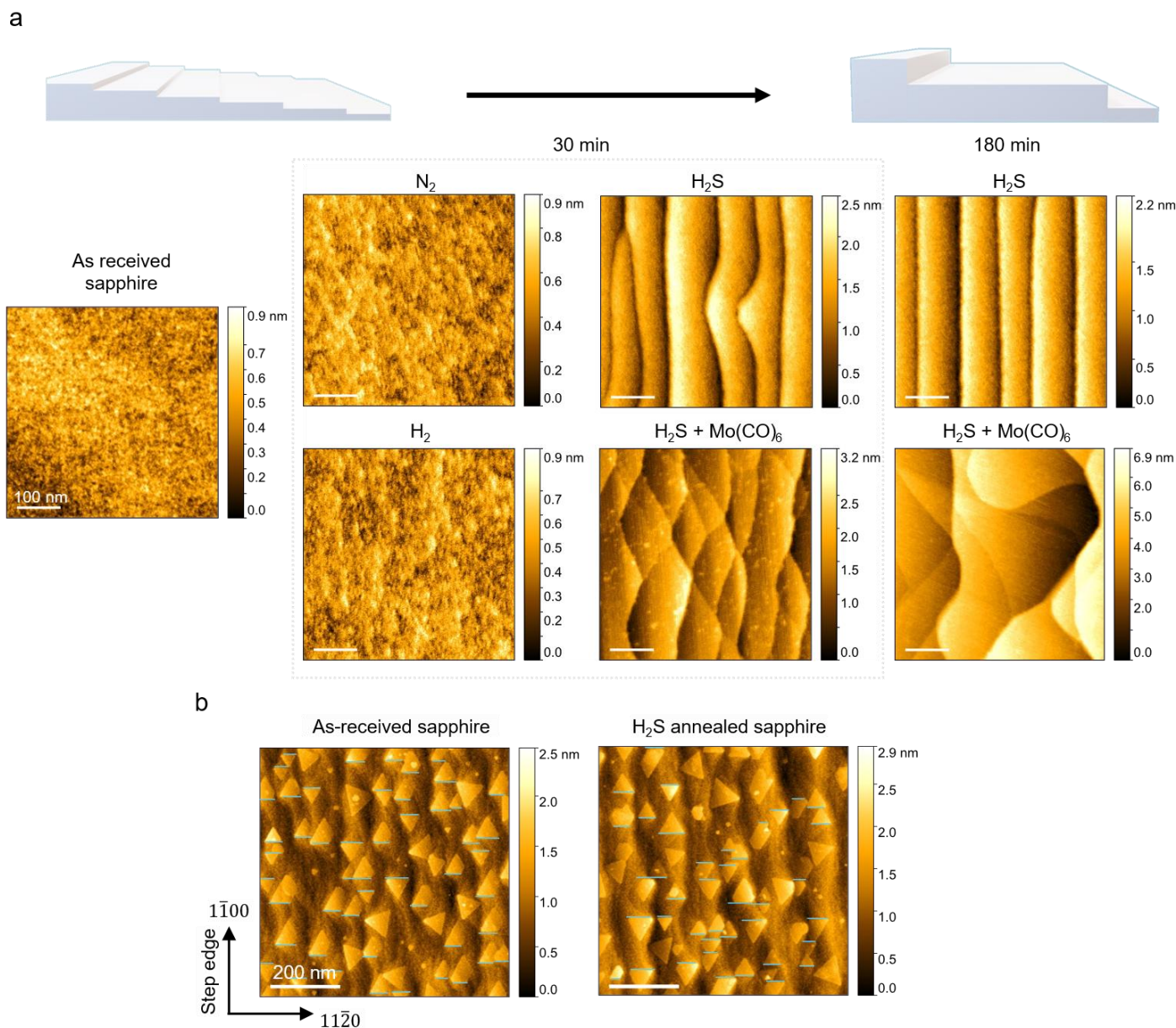


Figure S7. a, Changes of the sapphire surface depend on the chemicals present in the chamber during pretreatment at 1000 °C, as revealed by atomic force microscopy (AFM) images. For $H_2S + Mo(CO)_6$, MoS_2 is deposited on top of the sapphire surface and transferred prior to AFM imaging. **b**, The orientation of MoS_2 crystals is the same for as-received and H_2S -treated (30 min, 0.1 slm) sapphire. The deposition time is 30 minutes with 0.6 ppm of $Mo(CO)_6$.

The presence of steps on the sapphire surface can affect the shape of MoS₂ crystals. The steps on sapphire surface with the step edge along the [1-100] crystallographic direction can be generated when the off-cut direction is the [11-20] A-axis. For the R0° epitaxial relationship between the sapphire c-plane and the MoS₂ crystals, the triangular crystals are oriented perpendicular to the step edge. If the terrace width is much shorter than the diffusion length of the metal adatoms on the surface, anisotropic diffusion can be initiated.⁵ Here, we use off-A axis cut sapphire with a 1° off-axis cut angle and an initial terrace width of 12.4 nm, which further increases due to step coalescence. As a result, the MoS₂ crystals deposited with a metal precursor concentration of 0.1 ppm demonstrate anisotropic development of crystal facets, as we reported previously (**Figure S8a**)⁵. The crystal shape changes from triangular to diamond in a slow, step-by-step process, as depicted in Figure S3a. When the metal precursor concentration increases to 0.6 ppm, MoS₂ crystals shape follows the same anisotropic growth pathway as MoS₂ crystals at 0.1 ppm. However, at 0.6 ppm, different stages of crystal development coexist simultaneously, in contrast to step-by-step evolution observed at the lower metal precursor concentration (Figure S8b). Here, the higher adsorption rate causes the non-homogeneous distribution of metal adatoms on the surface. These adatoms exhibit anisotropic surface diffusion because of the steps present on the surface and sapphire surface reconstruction. As a result, facets of different crystals develop at varying speeds, as indicated by the different stages of shape evolution. When the metal concentration is further increased to 1.0 ppm, crystal coalescence starts very early in the deposition process because of high nucleation density, and no change in MoS₂ crystal shape is observed (Figure S8c).

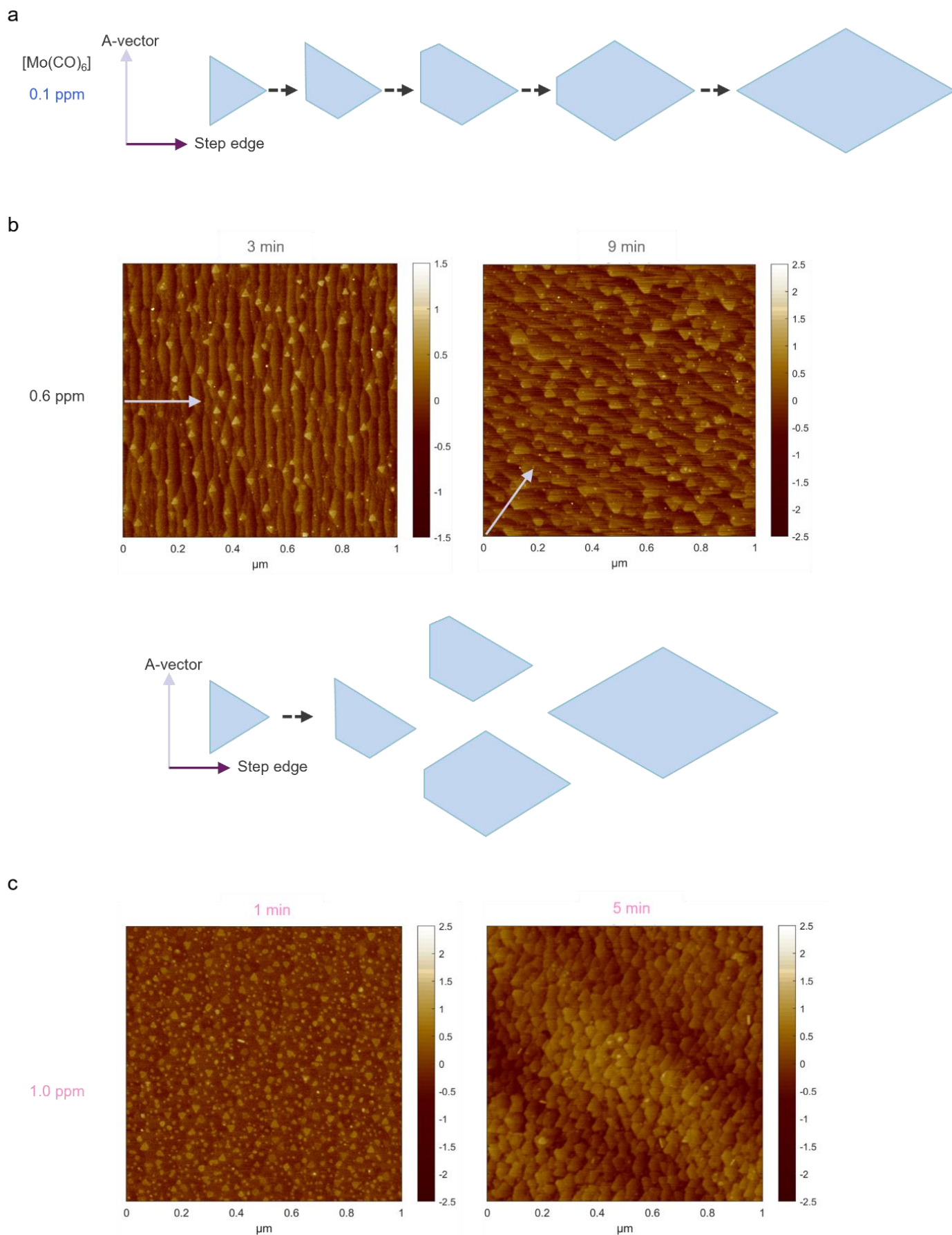


Figure S8. Schematic and AFM images of MoS₂ crystal shape evolution during MOCVD. The orientation of the A vector [11-20] is indicated by an arrow on the AFM images. **a**, Slow, step by step shape evolution at the lowest metal precursor concentration of 0.1 ppm. **b**, The different stages of crystal shape evolution coexist when the metal

precursor concentration is increased to 0.6 ppm. c, Crystal shape does not change at the higher metal precursor concentration of 1.0 ppm due to fast coalescence of the crystals.

Note 5. Recrystallization in multi-domain growth regime

The reduction of misoriented domains is a critical factor for optimizing performance and expanding the practical applications of 2D TMDs. The described van der Waals recrystallization process is highly beneficial to improve the crystallinity of the deposited MoS₂ monolayers, however, the energy required to recrystallize the misoriented domains depends on the structure of the formed grain boundaries. Following our experimental observations, effective 60° to 0° domains recrystallization during post deposition annealing (PDA) is possible in the MoS₂ monolayers, where the area of the 60° domains is below ≈ 20% upon the coalescence and the number of misoriented domains is below 1%. The β and γ grain boundary between the twin domains can be eliminated by one Mo or two S planes gliding, whereas a more complex mechanism is required to restore the high angle grain boundaries formed by the intermediate misoriented orientation towards the 0° orientation. In the case of the MoS₂ domains with the intermediate orientations, higher energy might be required to initiate the van der Waals recrystallization process, similar to the 3D materials recrystallization.⁶ As a result, MoS₂ monolayers with the higher content of the misoriented domains (deposited with 1.0 and 1.3 ppm of Mo (CO)₆) do not recrystallize completely to the single-crystalline monolayer after 10 minutes recrystallization process (Figure 4a).

The extra energy for the van der Waals recrystallization of the intermediate oriented domains can be given by prolonged recrystallization time. Indeed, the misoriented domains coverage decreases from 40% to 15% when increasing the PDA time from 10 to 15 minutes (**Figure S9**). Moreover, the improved crystallinity of the MoS₂ monolayer after longer PDA is indicated by the sharpened GI-XRD peak along [11-20] direction (Figure S9d). The full width at half maximum (FWHM) of the peak decreases from 1.1 to 0.4 when the recrystallization time increases from 10 to 15 minutes, respectively. Furthermore, high-resolution scanning TEM (HR-STEM) confirms the presence of the remaining misoriented domains with the relative orientations of 15°, 20°, and 35° after 10 and 15 minutes of the PDA (Figure S9e, f, respectively). Thus, minimizing the number of misoriented domains before the layer coalescence is crucial to promote effective van der Waals recrystallization of those domains and to enable the self-oriented growth regime.

When optical spectroscopy is employed, the room temperature photoluminescence (RT-PL) response of MoS₂ monolayer grown in multi-domain regime shows significant differences between measurements taken under vacuum and those taken under non-vacuum conditions (**Figure S17b**). This suggests that the

removal of physisorbed species from the numerous defect sites reduces the excitonic responses under vacuum. Additionally, the defectivity of multi-domain MoS₂ was analyzed using three shorter recrystallization times (5-15 minutes) to assess the impact associated with the reduction of grain boundaries. This effect was also observed in the GI-XRD and DF-TEM responses (Figure S9c, d). A drastic improvement was noted in the ratio of integrated excitonic responses (I_{XD} vs I_{XA}) in cryogenic PL measurements when the recrystallization time was increased from 5 to 15 minutes (Figure S10a). The extracted defectivity index decreased from 9.4 to 5.8, and ultimately to 0.8, for the intervals of 5, 10, and 15 minutes of recrystallization processing time, respectively (Figure S10b). This improvement in the optical defectivity may be attributed to the reduced density of grain boundaries in the material after the recrystallization process. Despite the drastic improvement in the crystallinity of MoS₂ with the increasing recrystallization time, Raman derived strain/charge doping map demonstrates the slight change of the stain and the charge doping of the monolayer, similar to the single-crystalline MoS₂. This result indicates the role of the sapphire template/MoS₂ interaction on the Raman spectra.

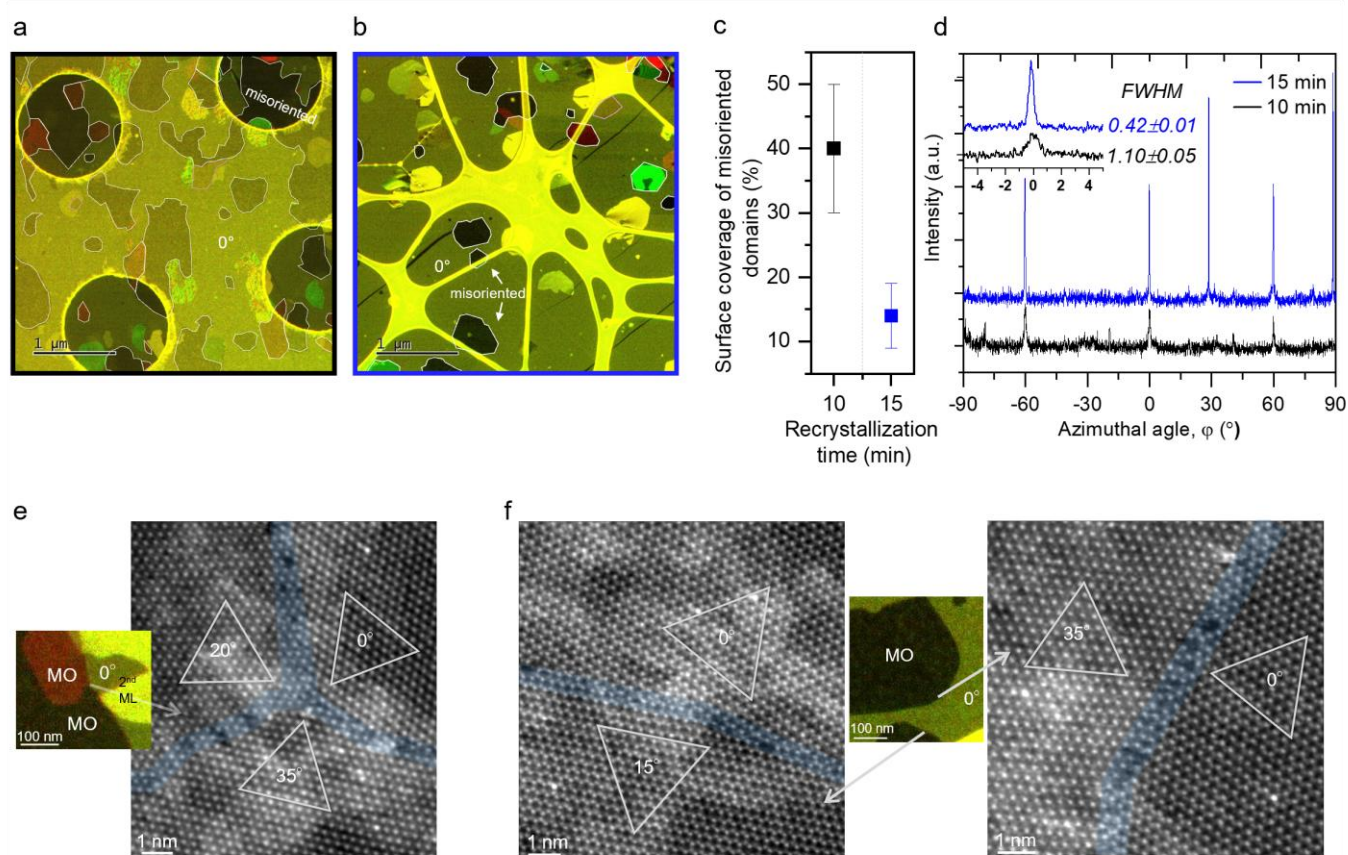
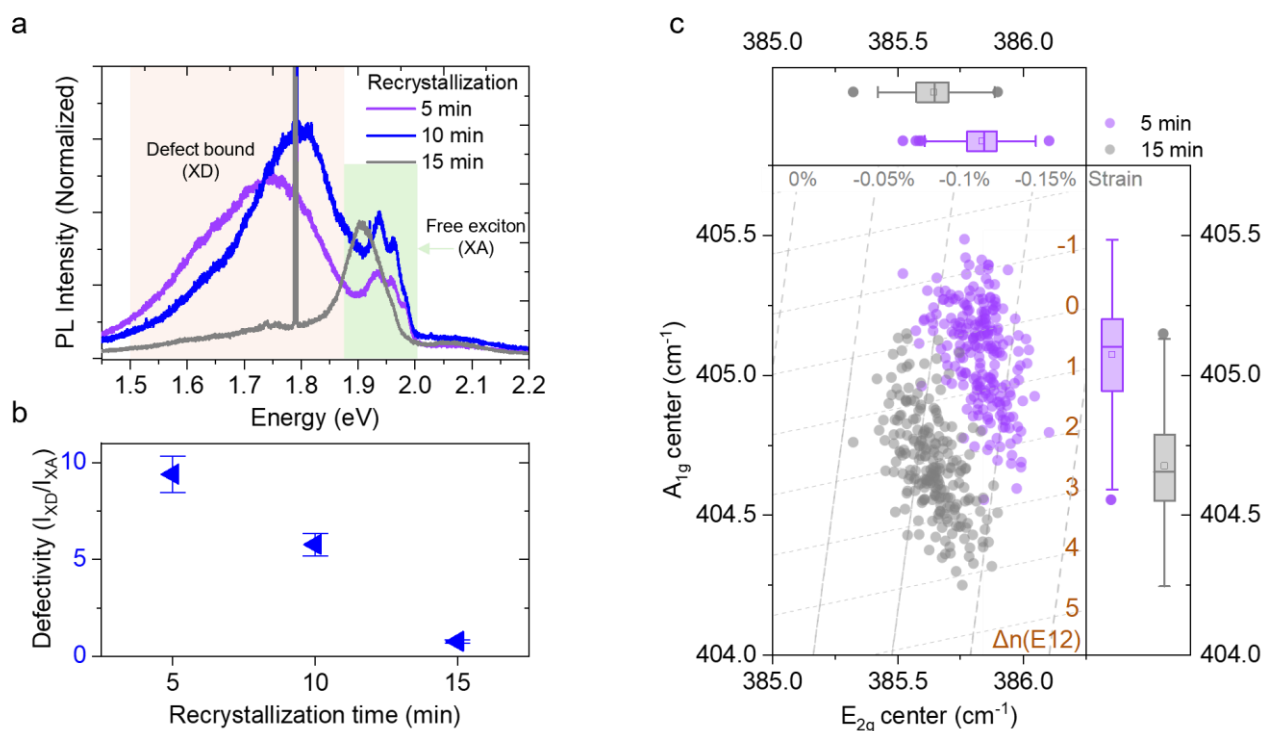


Figure S9. **a, b**, TEM images with false colors demonstrate the positive effect of prolonged PDA when the MoS₂ monolayer has a high number of misoriented domains. In the MoS₂ monolayer deposited with 1.0 ppm of Mo(CO)₆, after 10 minutes PDA, around 40% of the first monolayer consists of the misoriented (60° and intermediate) domains. **c**, The surface coverage of the misoriented domains decreases to 10% when PDA time increases from 10 to 15 minutes. **e, f**, HR-STEM images highlight the boundary area between the misoriented domains with relative 15°, 20°, 35°.

199 and 35° rotation after 10 (e) and 15 (f) minutes of recrystallization. The composite TEM image shows the large field
 200 of view of the inspected areas.

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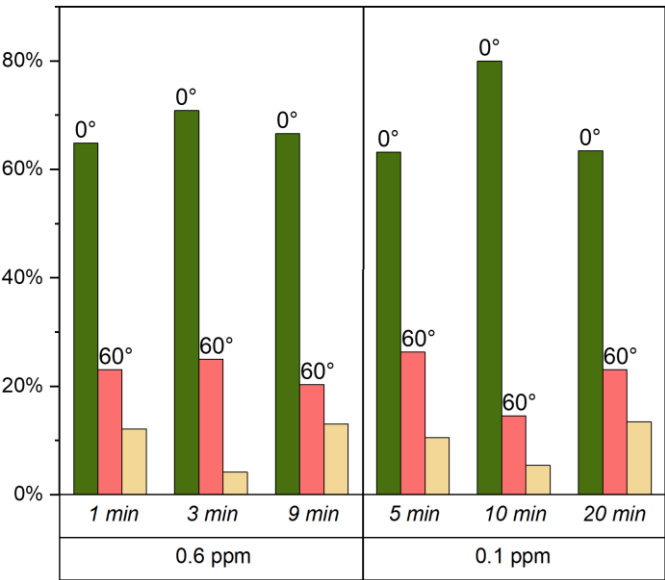


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203 **Figure S10.** Improved crystallinity with recrystallization time influences the optical response of MoS₂ monolayers
 204 growth in multidomain growth regime. **a**, Cryogenic PL at 78K demonstrate the notable spectra change for multi-
 205 domain MoS₂ monolayers with the recrystallization time. The deconvoluted spectra are presented in Figure S18. **b**,
 206 This is reflected in the extracted defectivity index (I_{XD} to I_{XA}), as a ratio of integral intensity of defect-bound to free
 207 excitons. **c**, Mapping A_{1g} and E_{2g} phonon peaks extracted from Raman spectra is used to assess strain and relative
 208 change in doping of MoS₂ monolayer during recrystallization. MoS₂ monolayers are deposited using 1.0 ppm of
 209 Mo(CO)₆.

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Supplementary figures

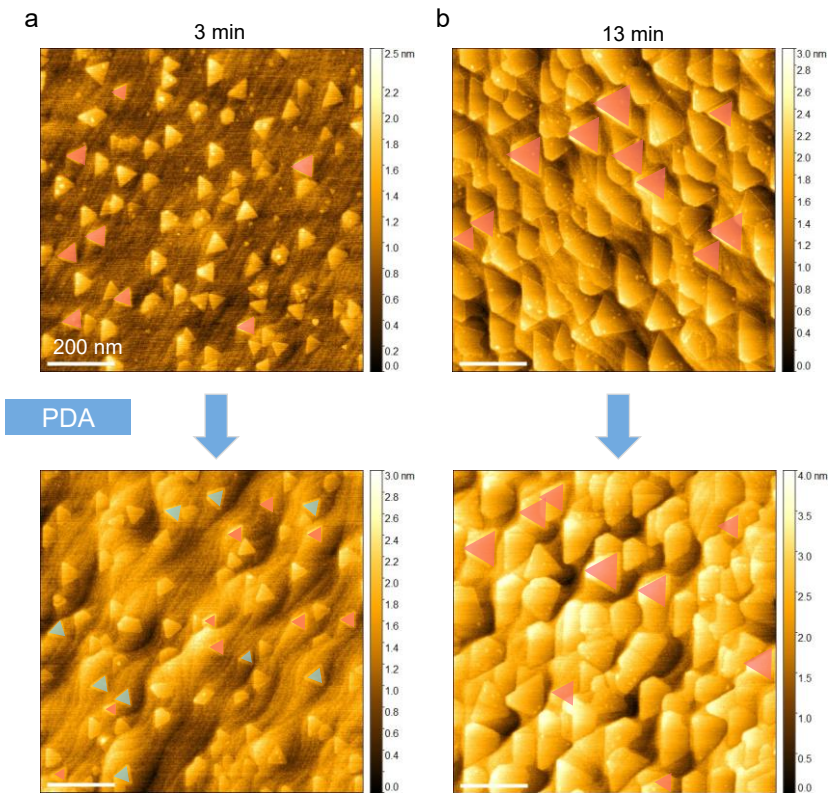


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Figure S11. Percentage of 0° and 60° oriented crystals (green and red, respectively) during the different growth stages of MoS₂ crystals deposited with 0.6 and 0.1 ppm. The misoriented crystals are indicated in orange.



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Figure S12. Effect of 10 min of post-deposition annealing (PDA) in H₂S on the orientation of the isolated MoS₂ crystals deposited with 0.6 ppm of Mo(CO)₆. Some 60° oriented crystals are highlighted in red. Transition 60° to 0° orientation is not observed. PDA causes more pronounced surface reconstruction and leads to an increase of the number of misoriented domains (in blue).

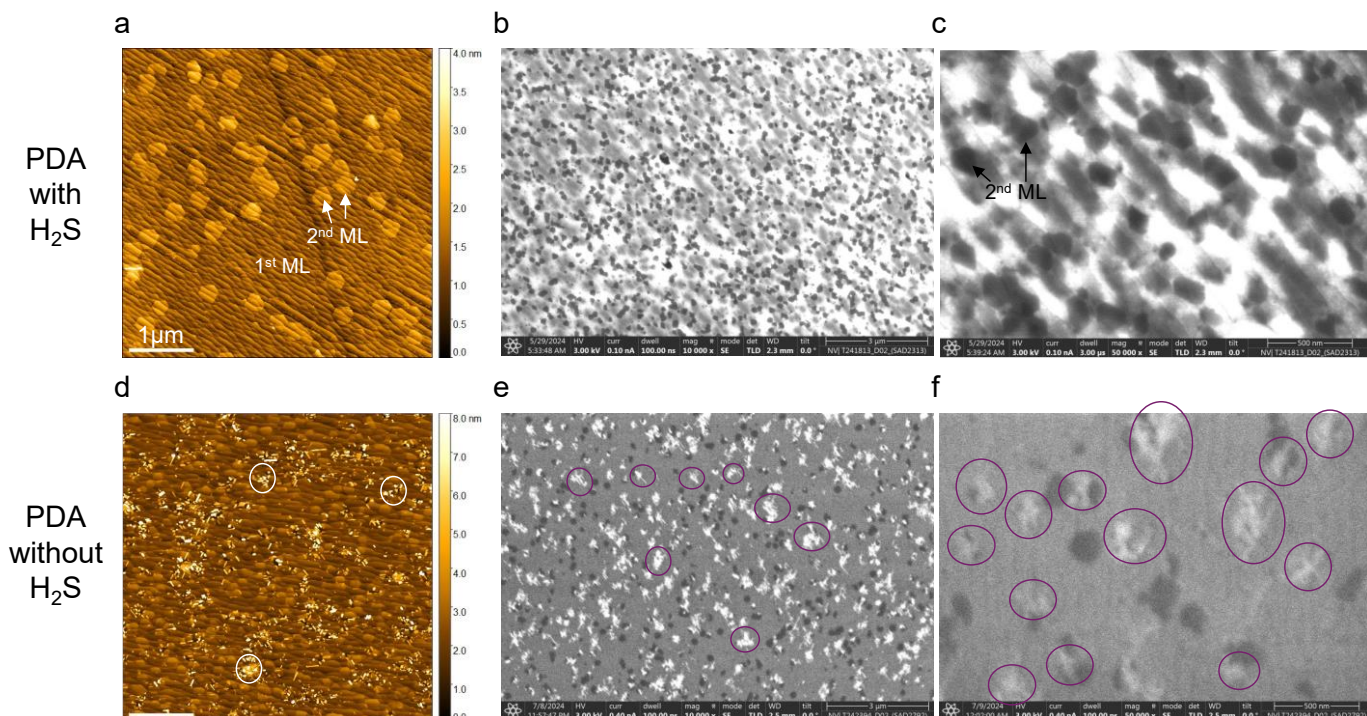


Figure S13. Effect of the atmosphere during 10 minutes of PDA at 1000 °C on the morphology of the closed MoS₂ monolayer deposited with 0.6 ppm of Mo(CO)₆. PDA without H₂S damages the first monolayer as well as the bilayer islands (indicated by the black arrows). The contrast in the SEM images of the closed MoS₂ monolayer is attributed to the water intercalation (b, c).

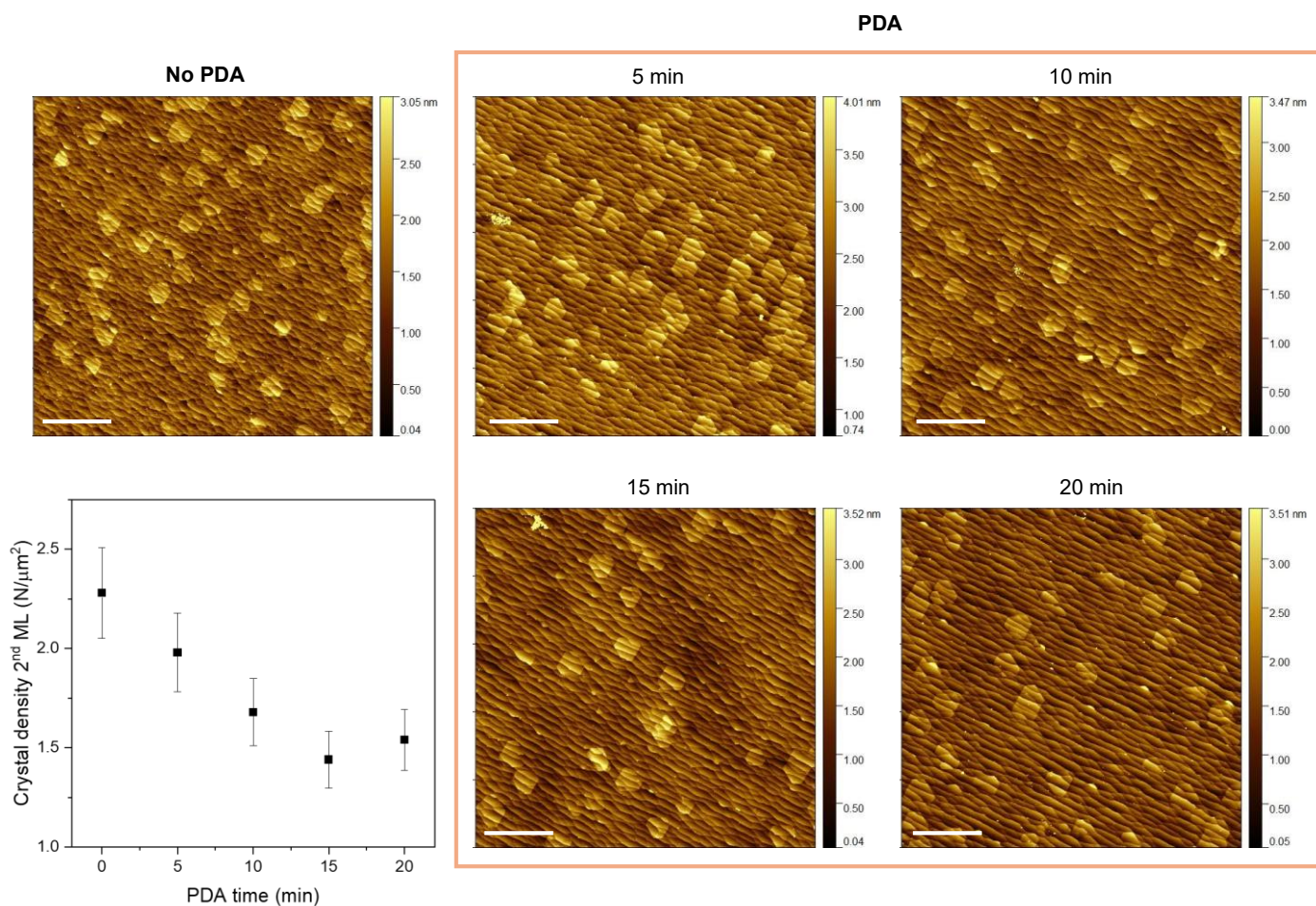


Figure S14. Decreasing 2nd MoS₂ monolayer crystal density with increasing PDA time. The MoS₂ monolayers are deposited with 0.6 ppm of Mo(CO)₆, and PDA is performed in H₂S at 1000 °C.

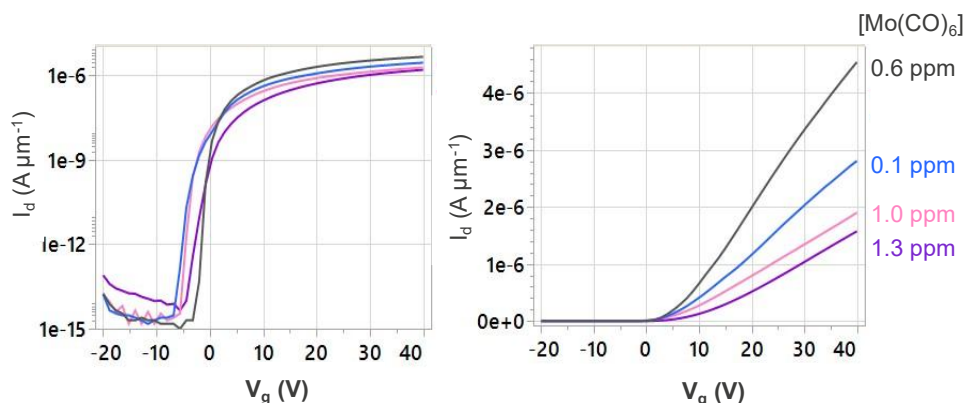
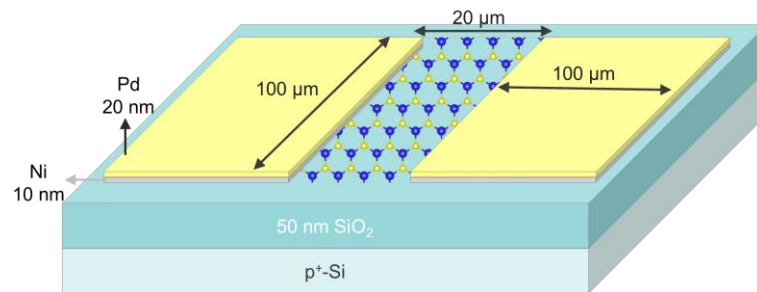


Figure S15. A schematic of the back-gated FET and drain current for MoS₂ monolayers presented in Figure 4c (top). The recrystallization time of 10 min is applied to all MoS₂ monolayers after a layer closure. A higher drain current (I_d) is observed for the lower metal precursor concentrations of 0.6 ppm and 0.1 ppm. A linear (right) and a logarithmic (left) scale are depicted as a function of gate voltage (V_g) for 1V drain voltage.

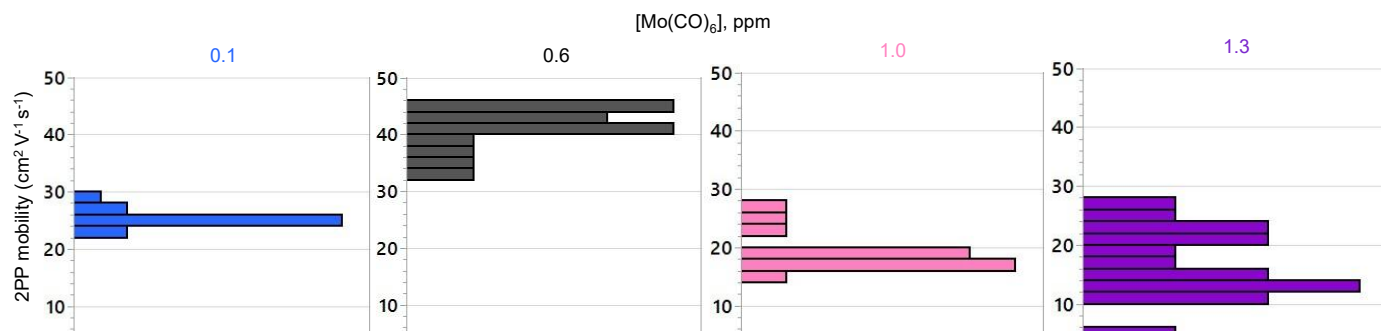


Figure S16. Statistical distribution of the 2pp mobility measured in the lab-fabricated back-gated FET with MoS₂ active layer.

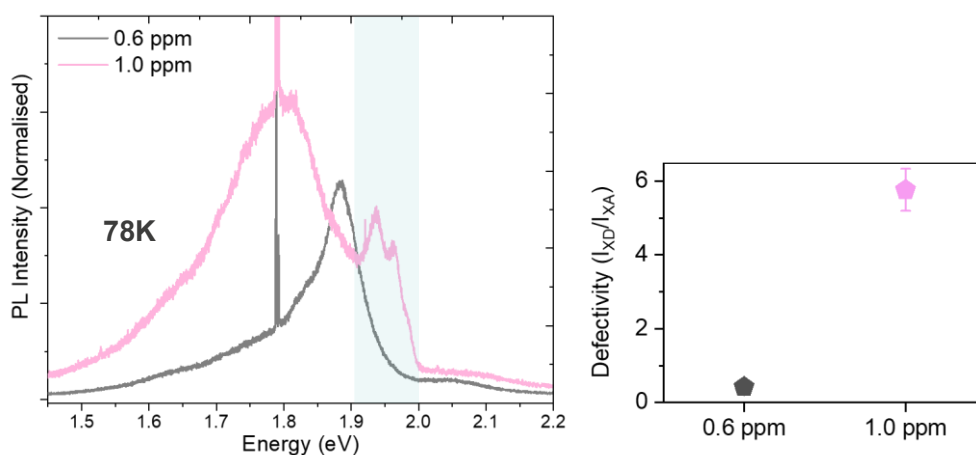


Figure S17. Cryogenic photoluminescence (PL) at 78K reveals a 98 meV shift (blue line) between singlecrystalline (0.6 ppm) MoS₂ monolayer and MoS₂ monolayer with misoriented domains (1.0 ppm) due to an impact of interface

charges. The defectivity index is extracted from cryogenic PL and is higher for the monolayers containing misoriented domains compared to single-crystalline MoS₂ monolayer.

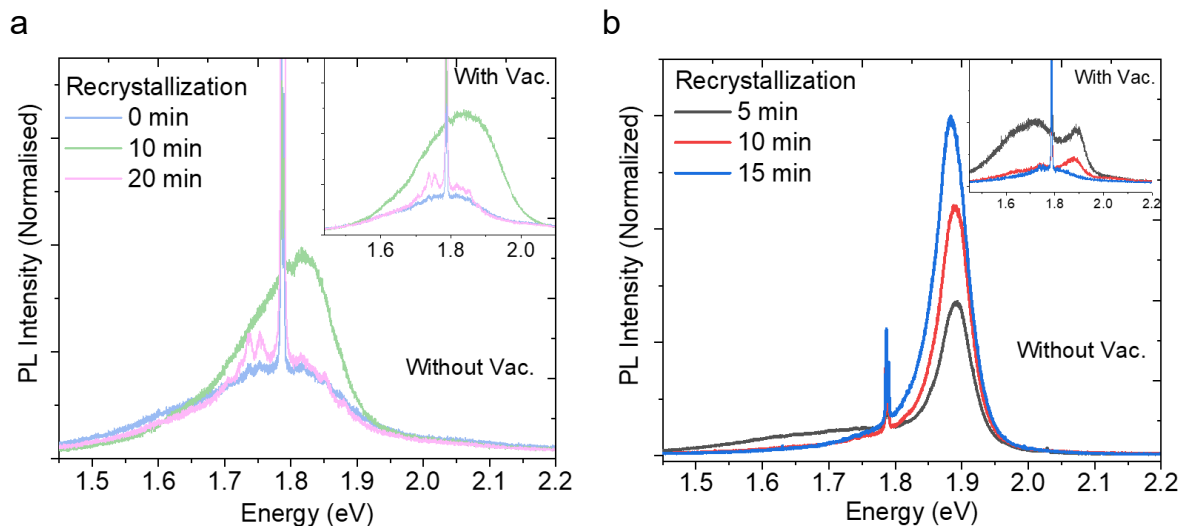
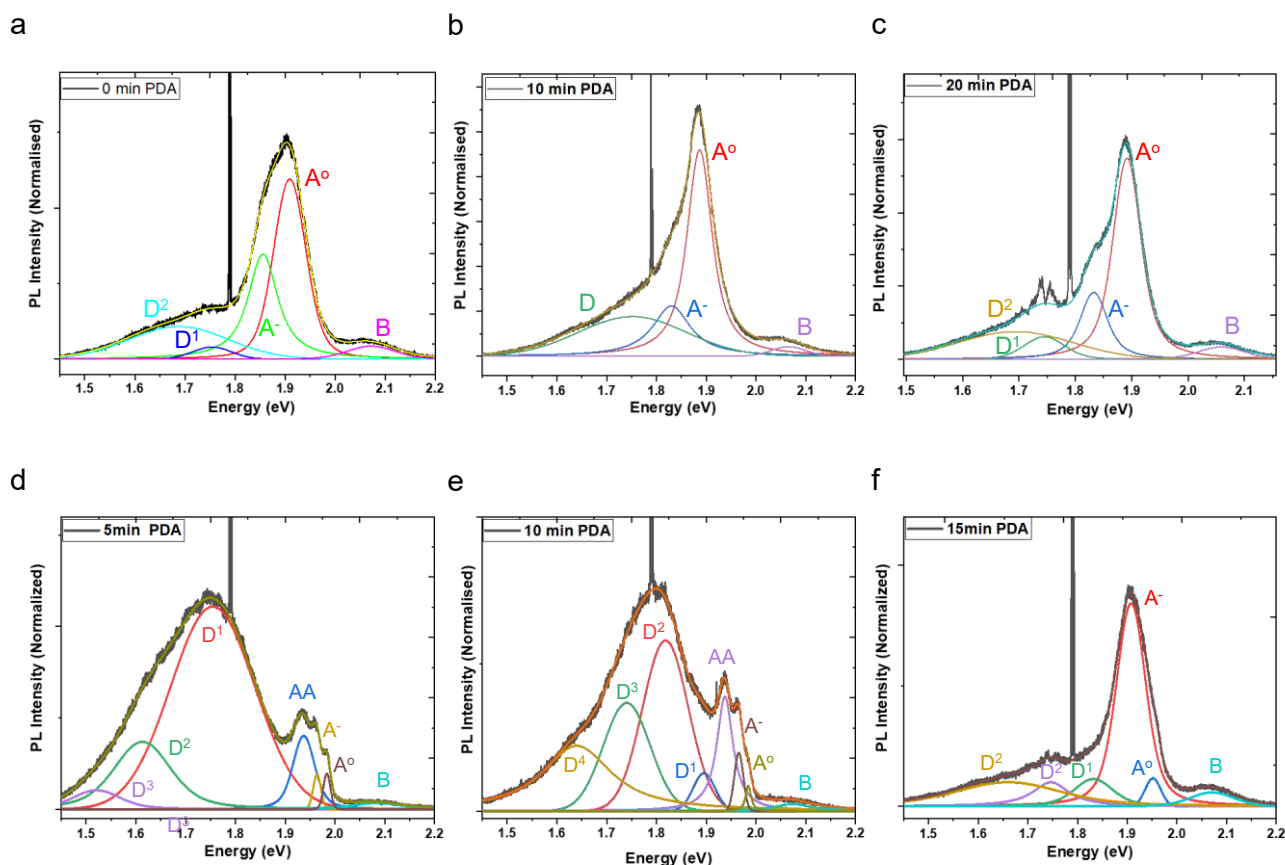
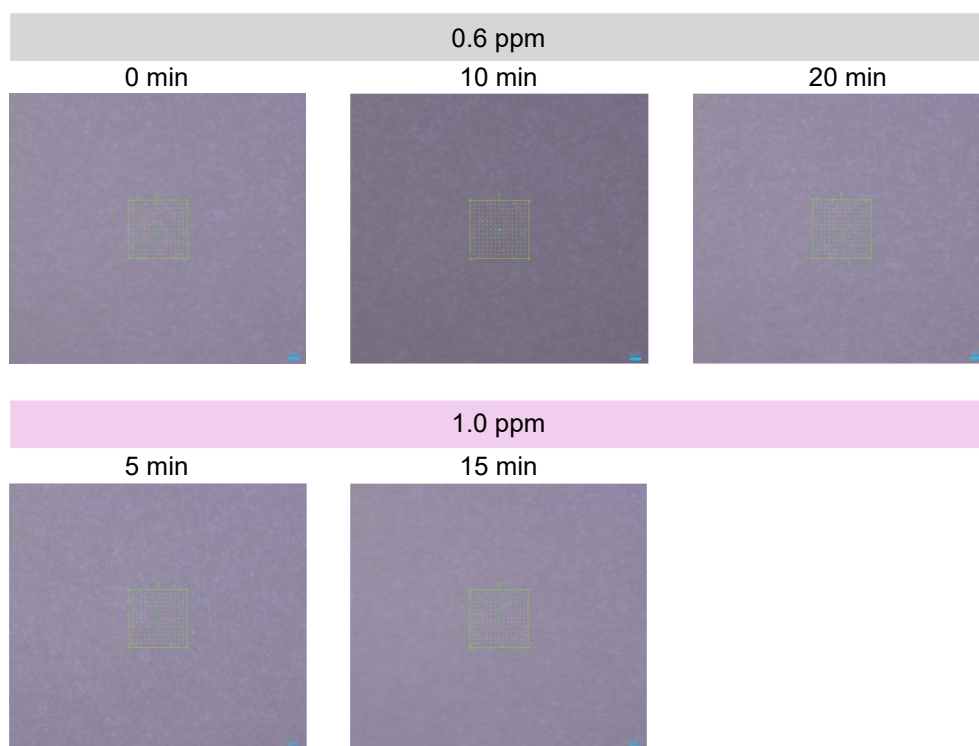


Figure S18. Room temperature photoluminescence (RT-PL) with and without vacuum for MoS₂ monolayers deposited with 0.6 (a) and 1.0 ppm (b) of Mo(CO)₆ after different recrystallization times. The room temperature responses tend to change significantly when transitioning from a non-vacuum to a vacuum environment. This is due to various atmospheric species, such as O₂, H₂O, and organic molecules, which can physisorb onto the defective surfaces (including grain boundaries) of monolayer MoS₂. **a**, Here, the negligible differences in RT-PL responses between the vacuum and non-vacuum conditions confirm the high quality and lower presence of defect centers in the single-crystalline MoS₂ monolayer grown in self-oriented growth regime. **b**, This is in contrast with MoS₂ monolayers grown in multi-domain regime, where a pronounce difference in RT-PL is observed between vacuum and non-vacuum conditions.



252 **Figure S19.** Deconvolution of the cryogenic PL at 78K from Figure 5a and -d after different recrystallization times
 253 using the Lorentzian function. MoS₂ monolayers were deposited with 0.6 (a, b, c) and 1.0 ppm (d, e, f) of Mo(CO)₆.
 254 The spectra in (a, b, c) and (d, e, f) correspond to Figure 5a and -d, respectively. A⁰, A⁻, AA, B, and D correspond to
 255 neutral exciton, charged exciton (trion), biexciton, B exciton, and low temperature defect bands, respectively. If the
 256 fitting results in the few defect bands, they are numbered D¹, D², etc.

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259 **Figure S20.** Optical images of the areas where 225 Raman spectra were acquired of MoS₂ monolayers on sapphire
 260 deposited with 0.6 and 1.0 ppm of Mo(CO)₆.

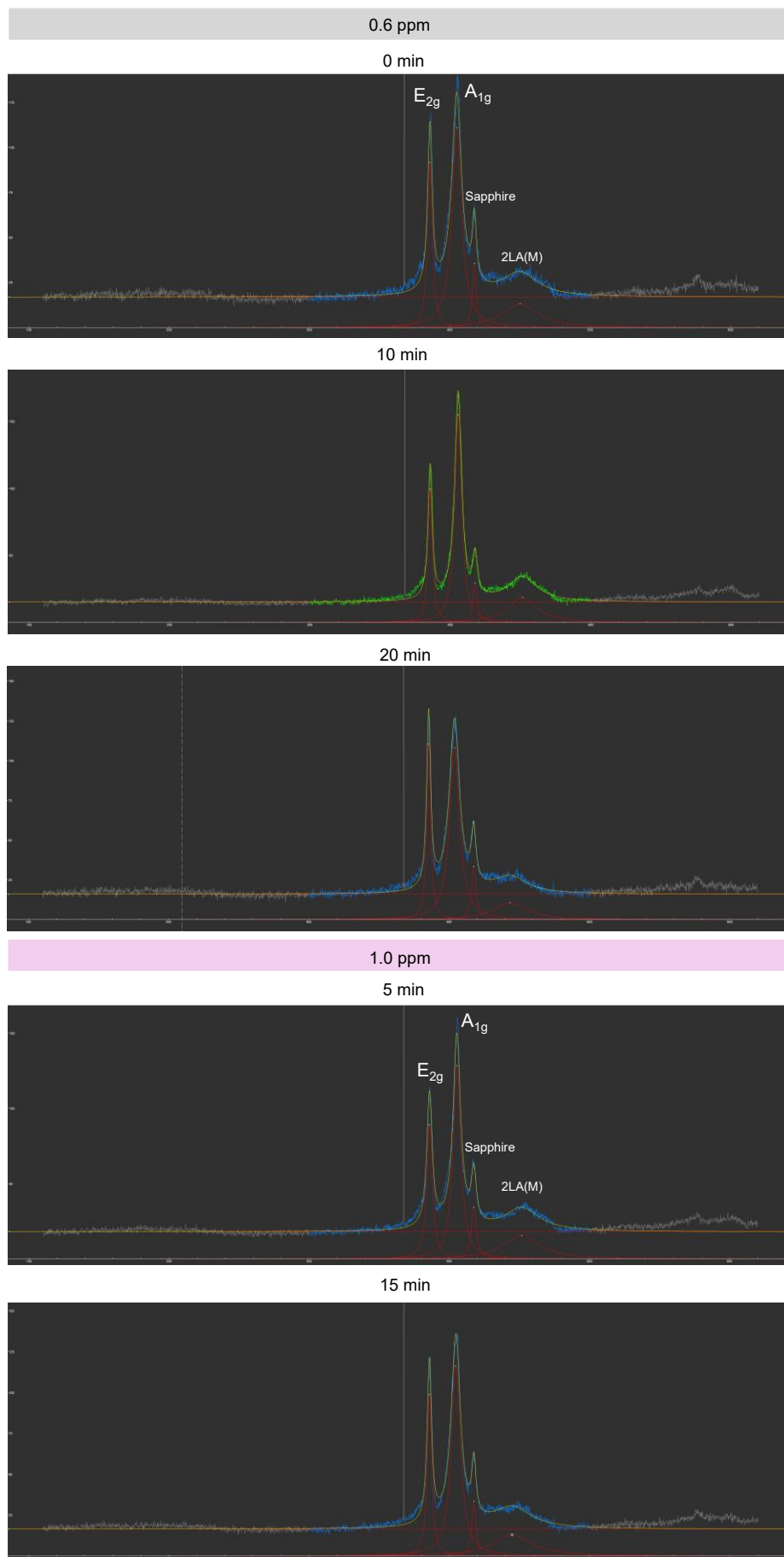


Figure S21. Typical Raman spectral response, obtained from MoS₂ monolayer deposited with 0.6 and 1.0 ppm of Mo(CO)₆ after different recrystallization times.

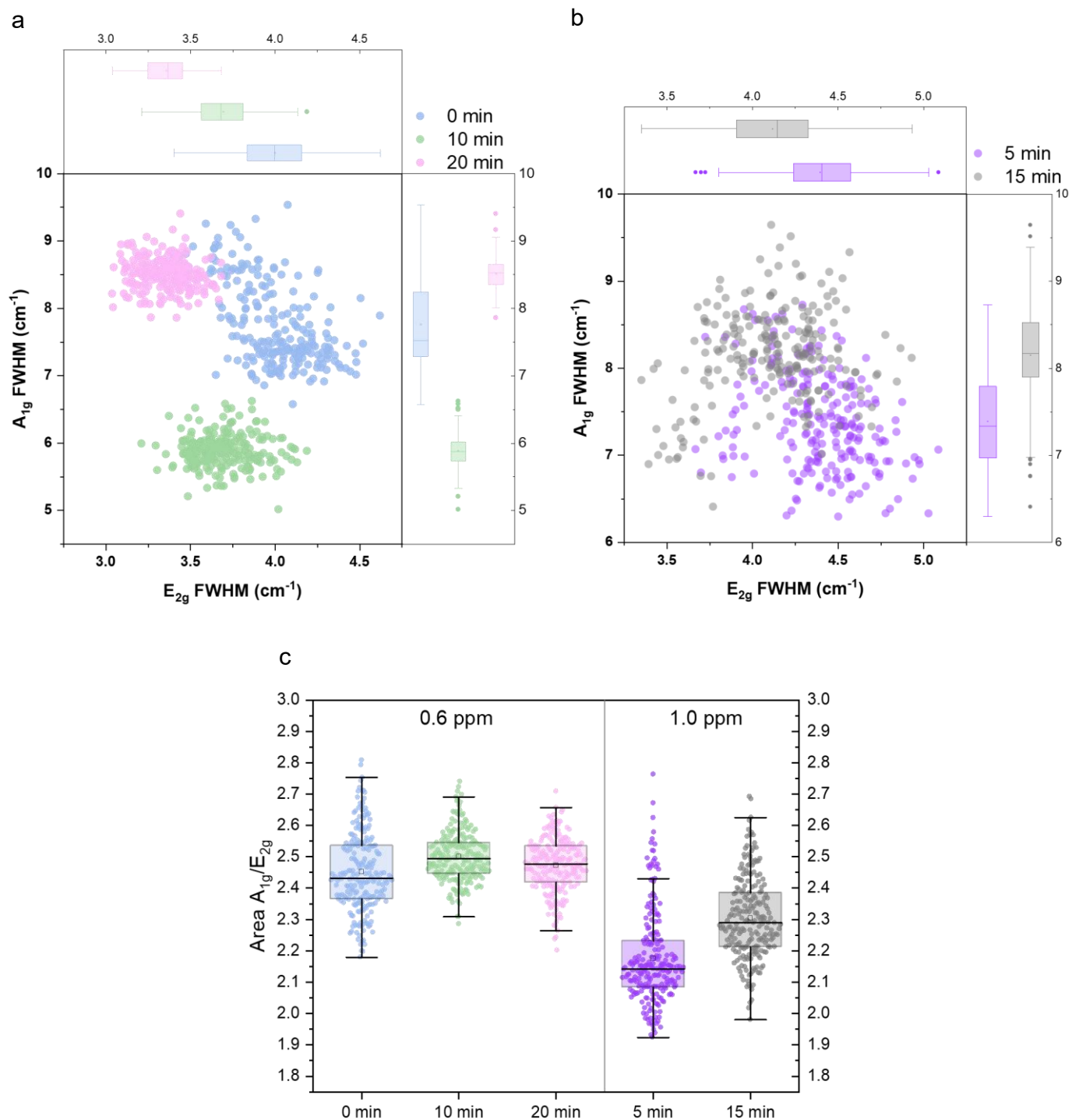
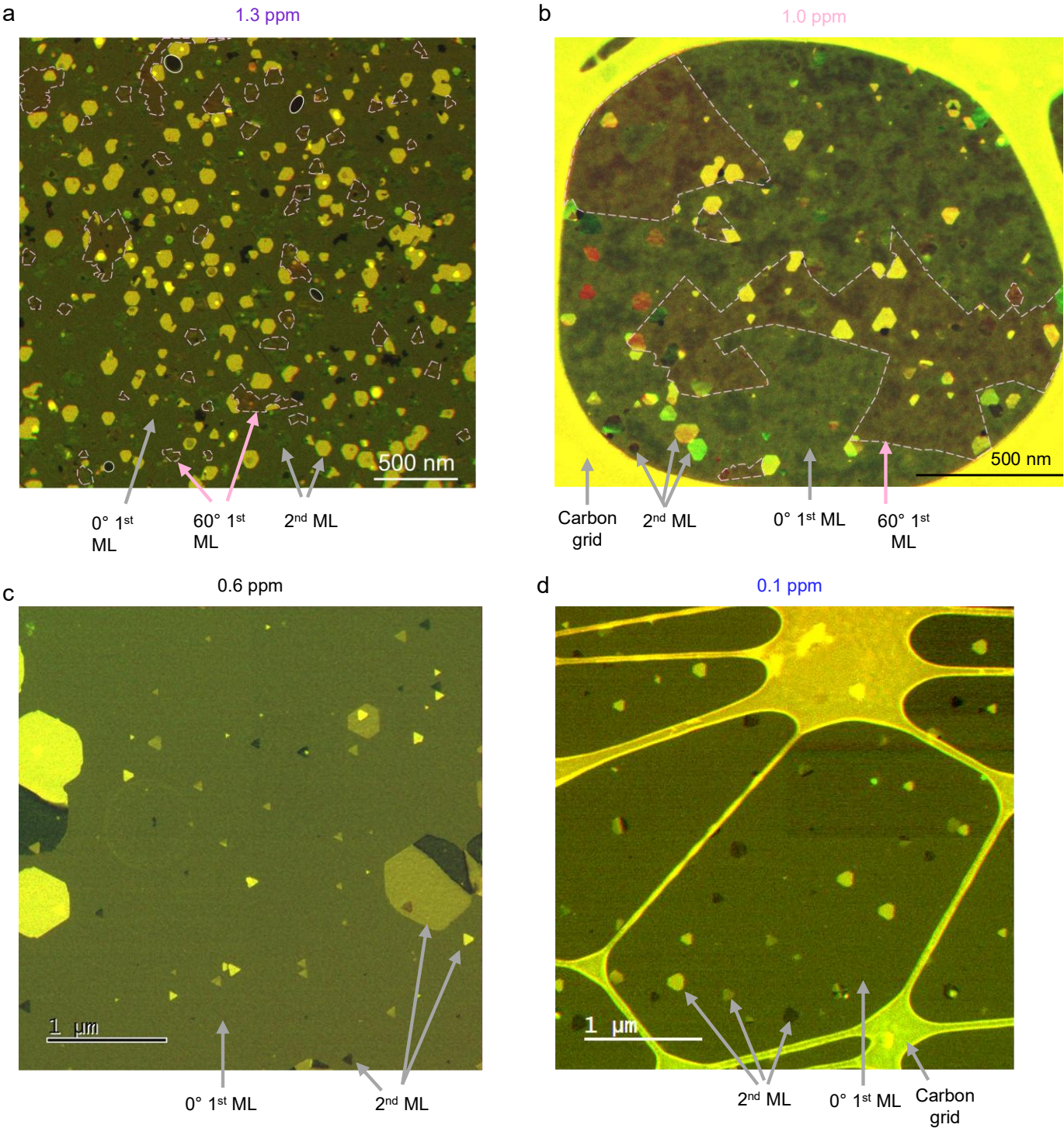


Figure S22. Statistical interpretation of the extracted A_{1g} and E_{2g} peaks from Raman spectral response, obtained from MoS₂ monolayer deposited with 0.6 (a) and 1.0 ppm (b) of Mo(CO)₆ after different recrystallization times.



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Figure 23. Large field of view composite TEM images of MoS₂ monolayers presented in Figure 4a.

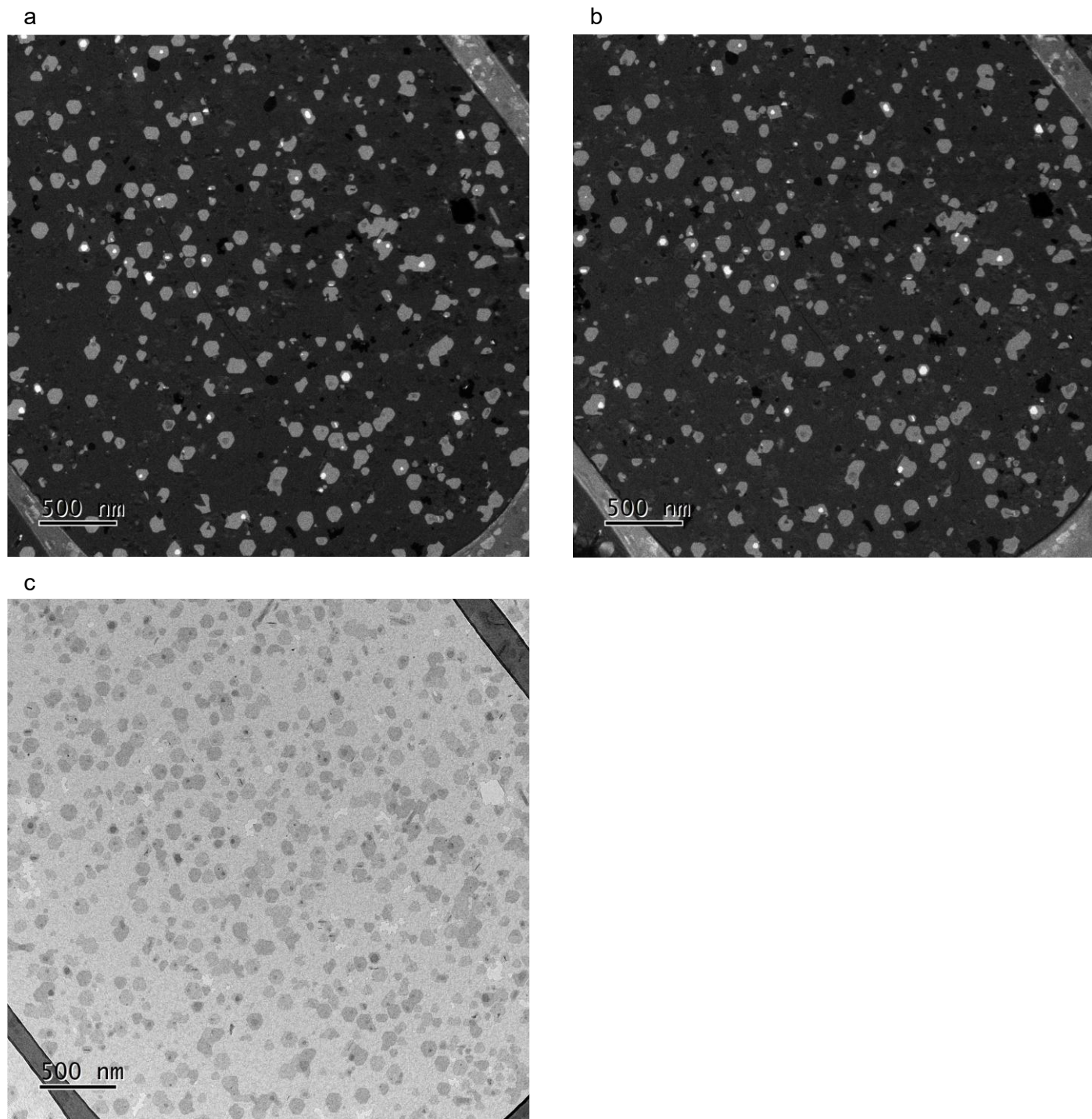


Figure S24. The dark-field TEM images (a, b) of the MoS_2 monolayer used for the composite image with false colors in Figure S23a. A bright-field TEM image of the same area is presented in (c).

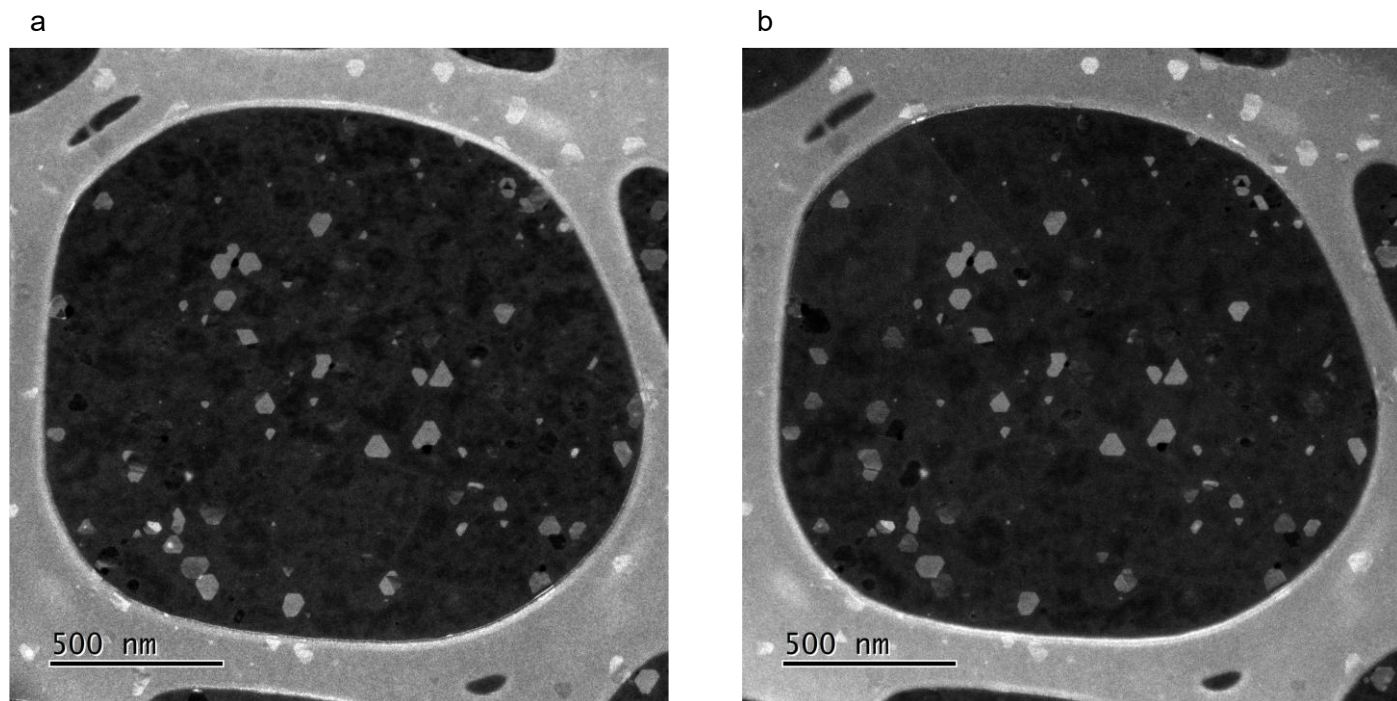


Figure S25. The dark-field TEM images (a, b) of the MoS₂ monolayer used for the composite image with false colors in Figure S23b.

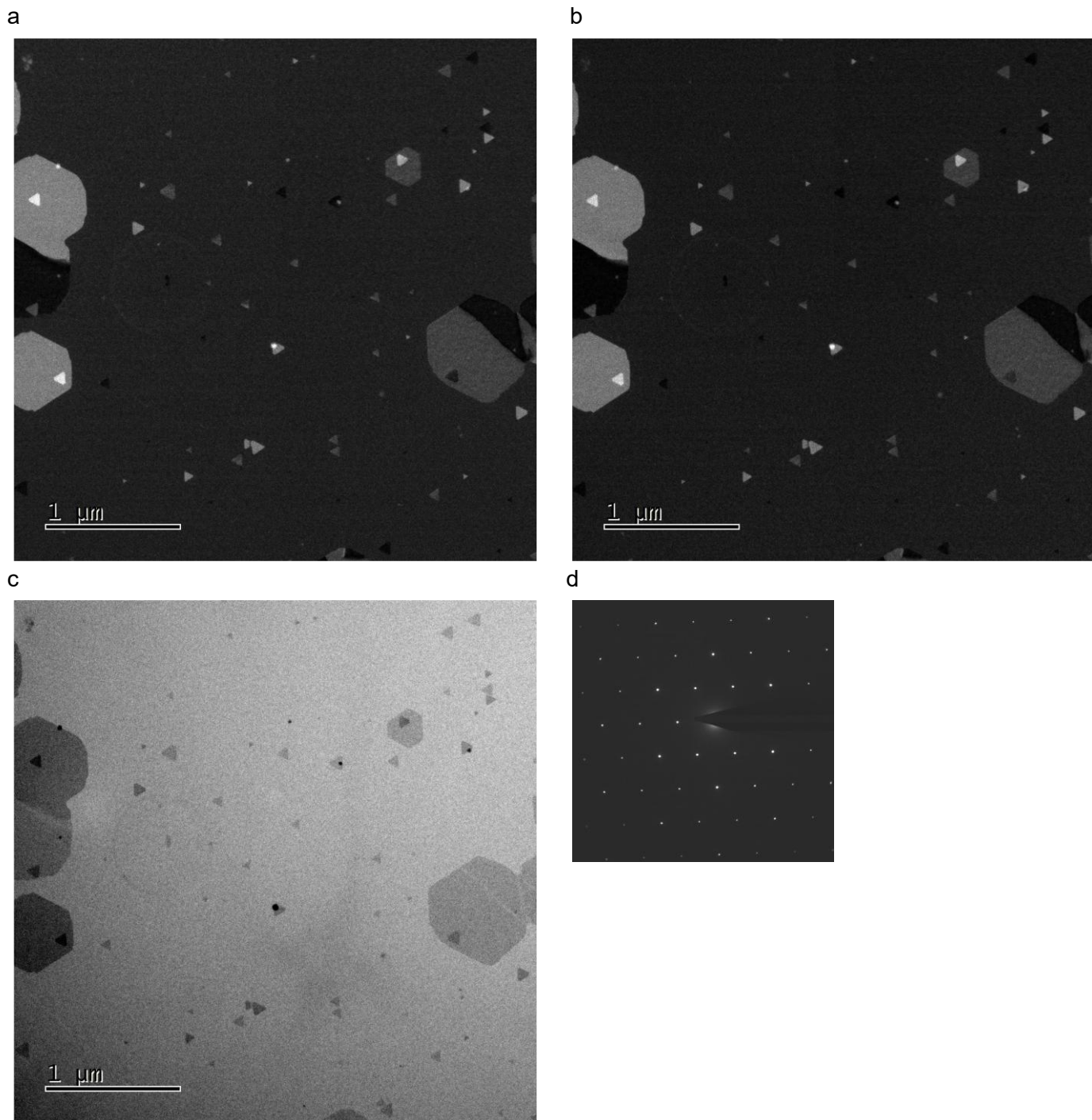


Figure S26. The dark-field TEM images (a, b) of the MoS₂ monolayer used for the composite image with false colors in Figure S23c. A bright-field TEM image and a diffraction pattern of the same area is presented in (c) and (d), respectively.

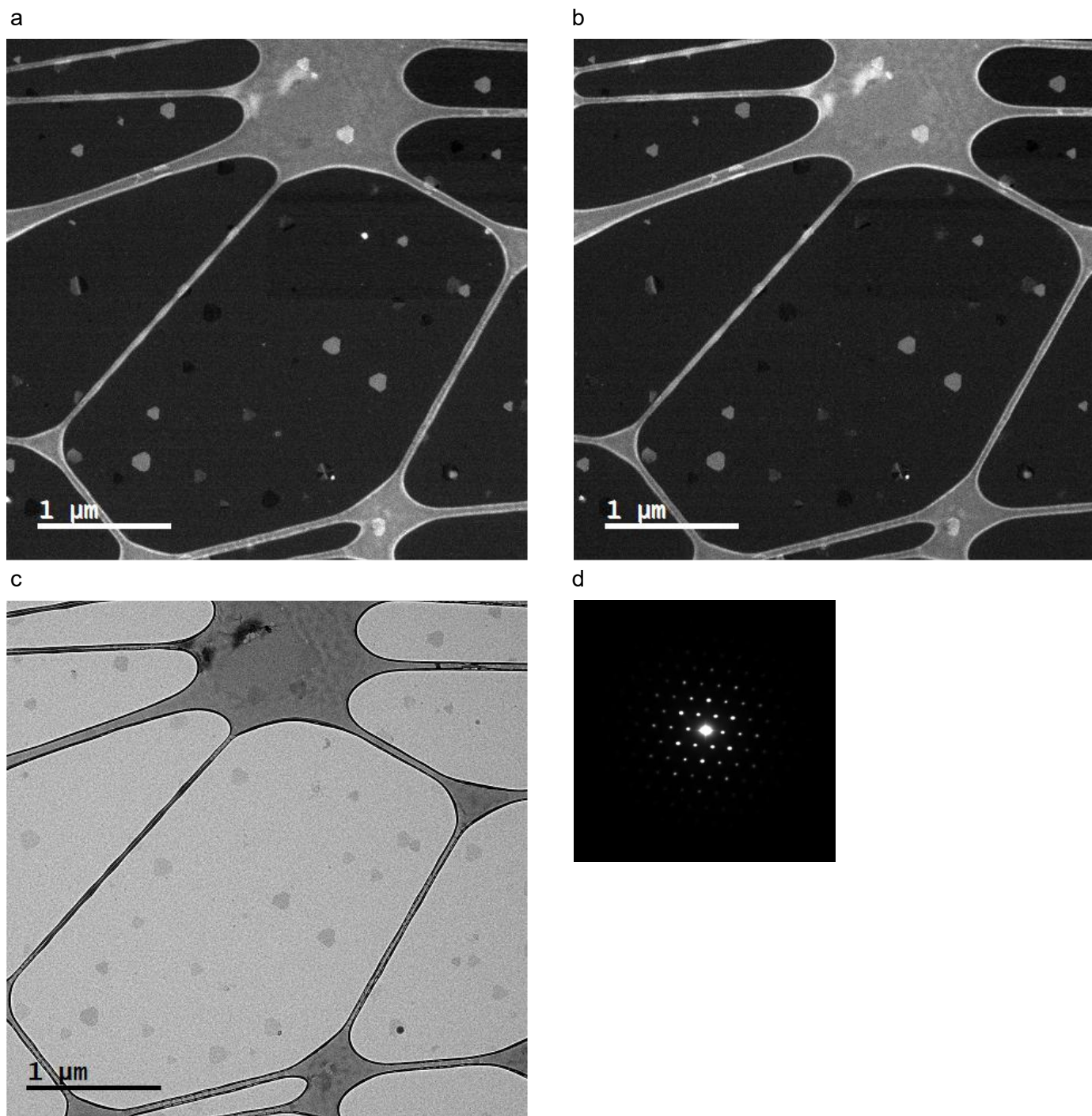


Figure S27. The dark-field TEM images (a, b) of the MoS₂ monolayer used for the composite image with false colors in Figure S23d. A bright-field TEM image and a diffraction pattern of the same area is presented in (c) and (d), respectively.

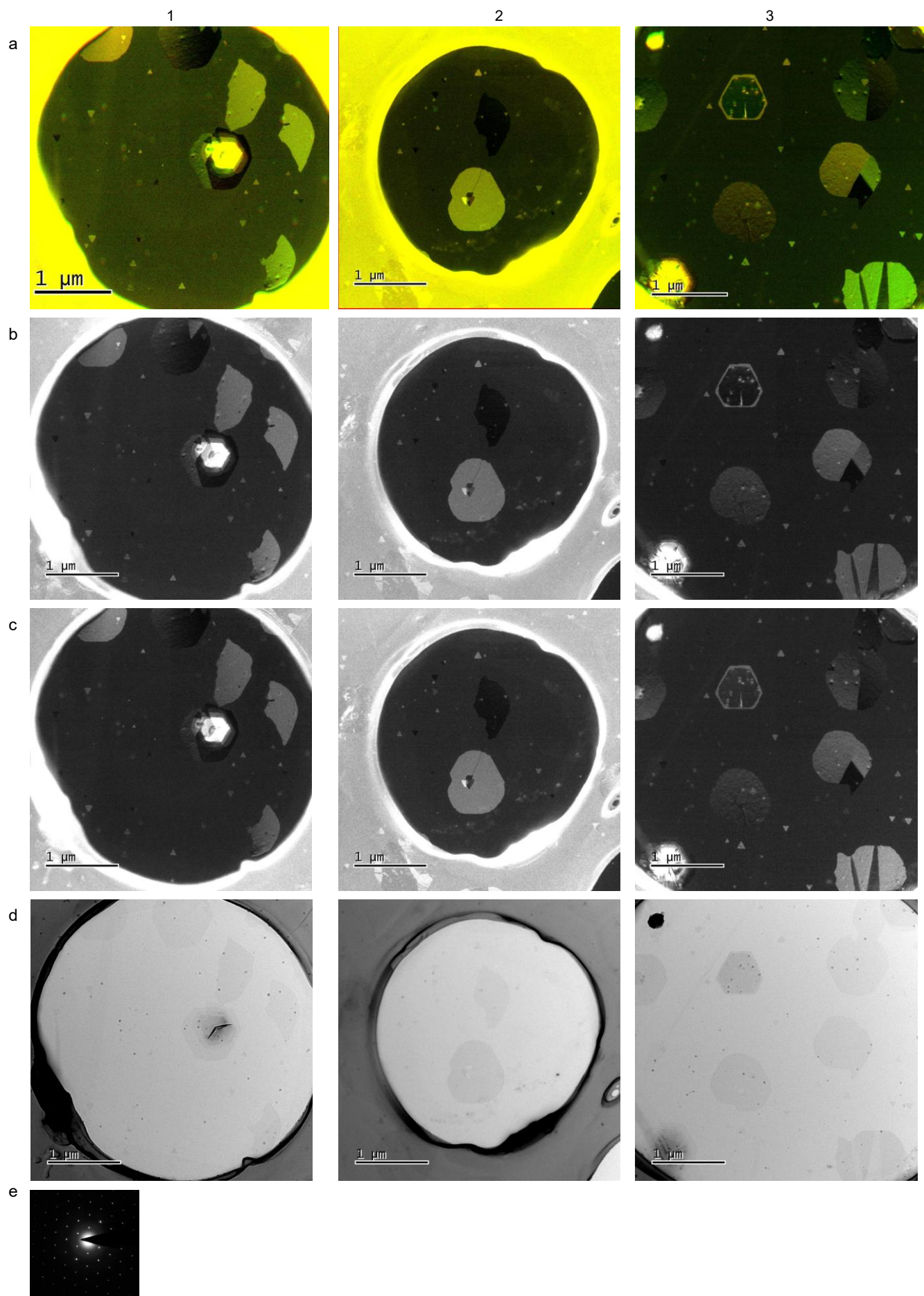


Figure S28. The additional TEM images from 3 regions for the MoS₂ monolayers deposited with 0.6 ppm of Mo(CO)₆, demonstrating the single-crystalline nature of the film. The composite images with false colors (a) are composed

290 using the dark-field TEM images (b, c). The bright-field TEM images and a diffraction pattern of the same area are
291 presented in (d) and (e), respectively.

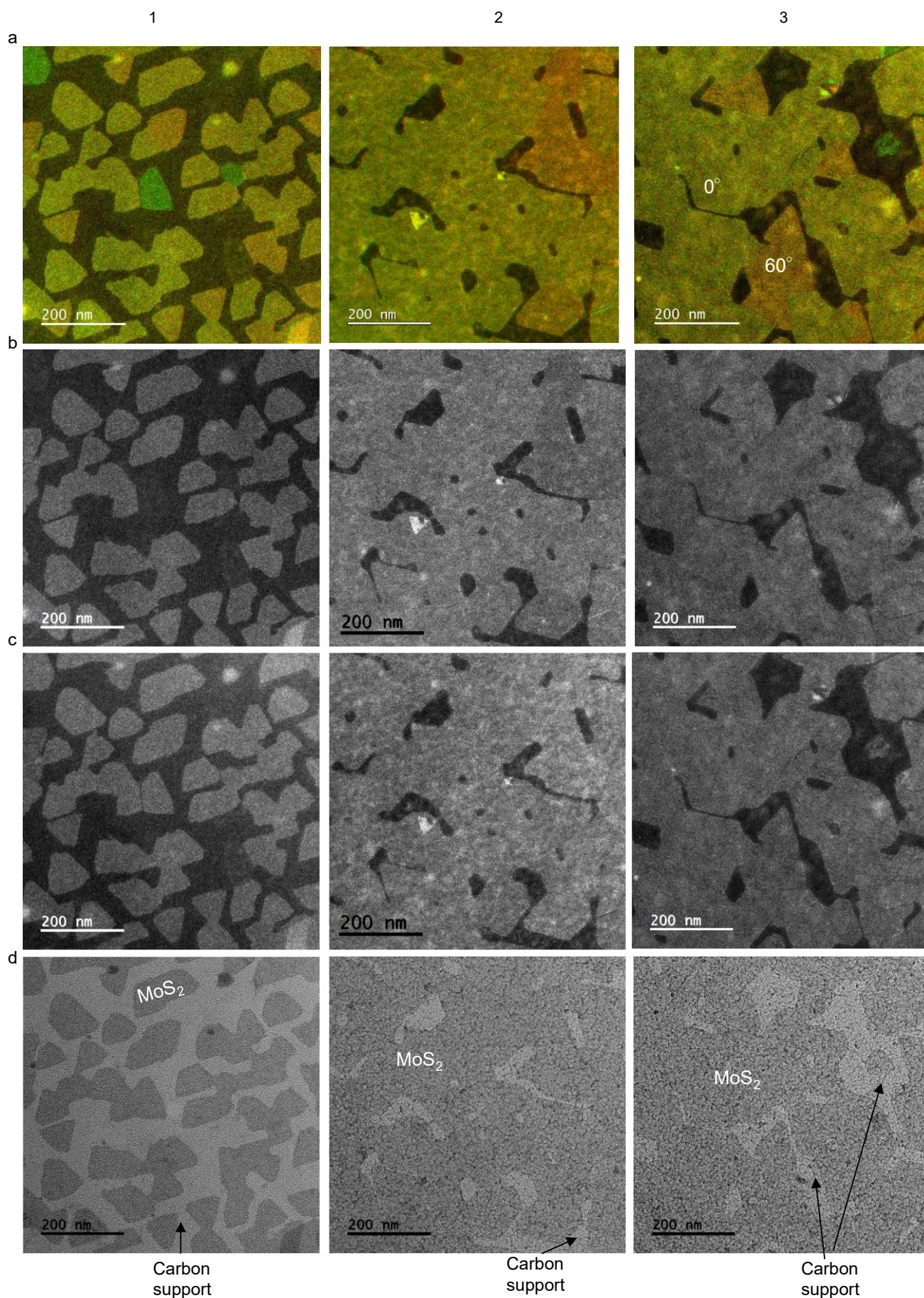


Figure S29. The TEM images from 3 of the MoS₂ crystals deposited with 0.6 ppm of Mo(CO)₆ for 13 min (1) and 19 min (2 and 3). The composite images with false colors (a) are composed using the dark-field TEM images (b, c). The bright-field TEM images are presented in (d). The composite images from regions 1 and 2 were used in Figure 2b.

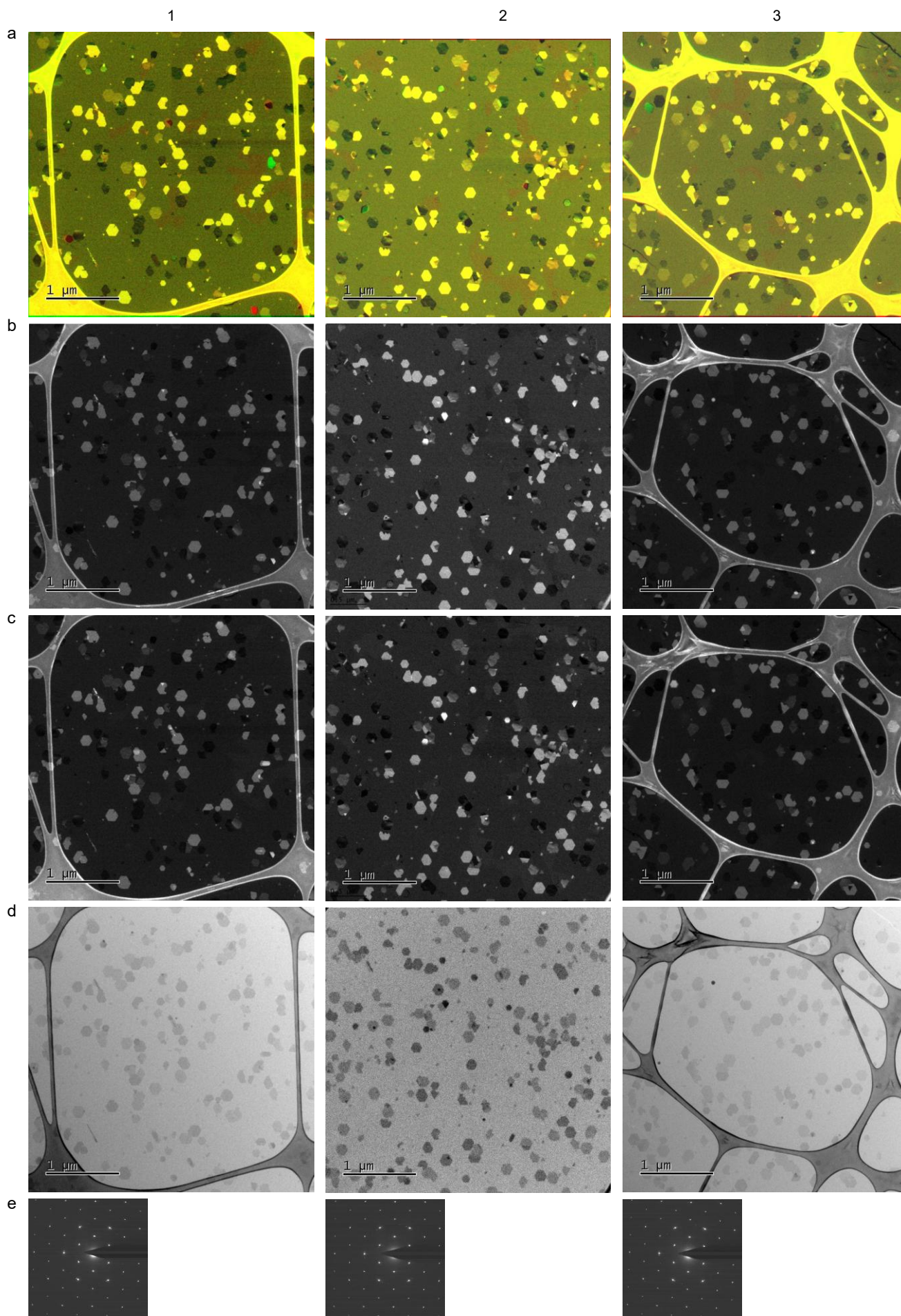


Figure S30. The TEM images from 3 regions for the MoS₂ monolayer deposited with 0.6 ppm of Mo(CO)₆ for 22 min (Sample 1). The composite images with false colors (a) are composed using the dark-field TEM images (b, c). The red

299 areas on the composite images correspond to twin domains. The bright-field TEM images and the diffraction patterns
300 are presented in (d) and (e), respectively. The composite image from region 2 was used in Figure 2b.

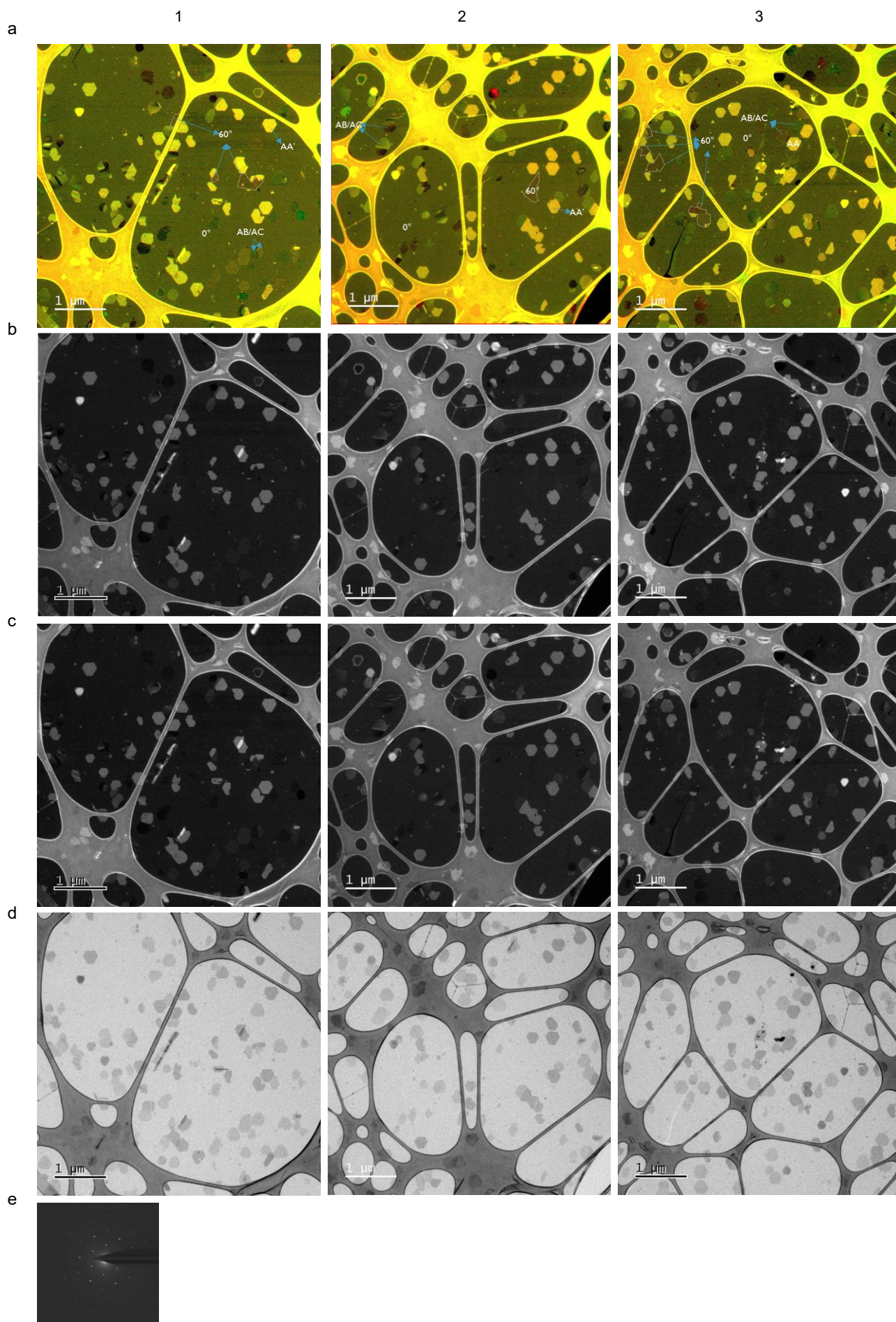


Figure S31. The TEM images from 3 regions for the MoS₂ monolayer deposited with 0.6 ppm of Mo(CO)₆ for 22 min (Sample 2). The composite images with false colors (a) are composed using the dark-field TEM images (b, c). The red

304 areas on the composite images correspond to twin domains, as highlighted on the images. The stacking of the second
305 layer islands is also highlighted. The bright-field TEM images and a diffraction pattern are presented in (d) and (e),
306 respectively.

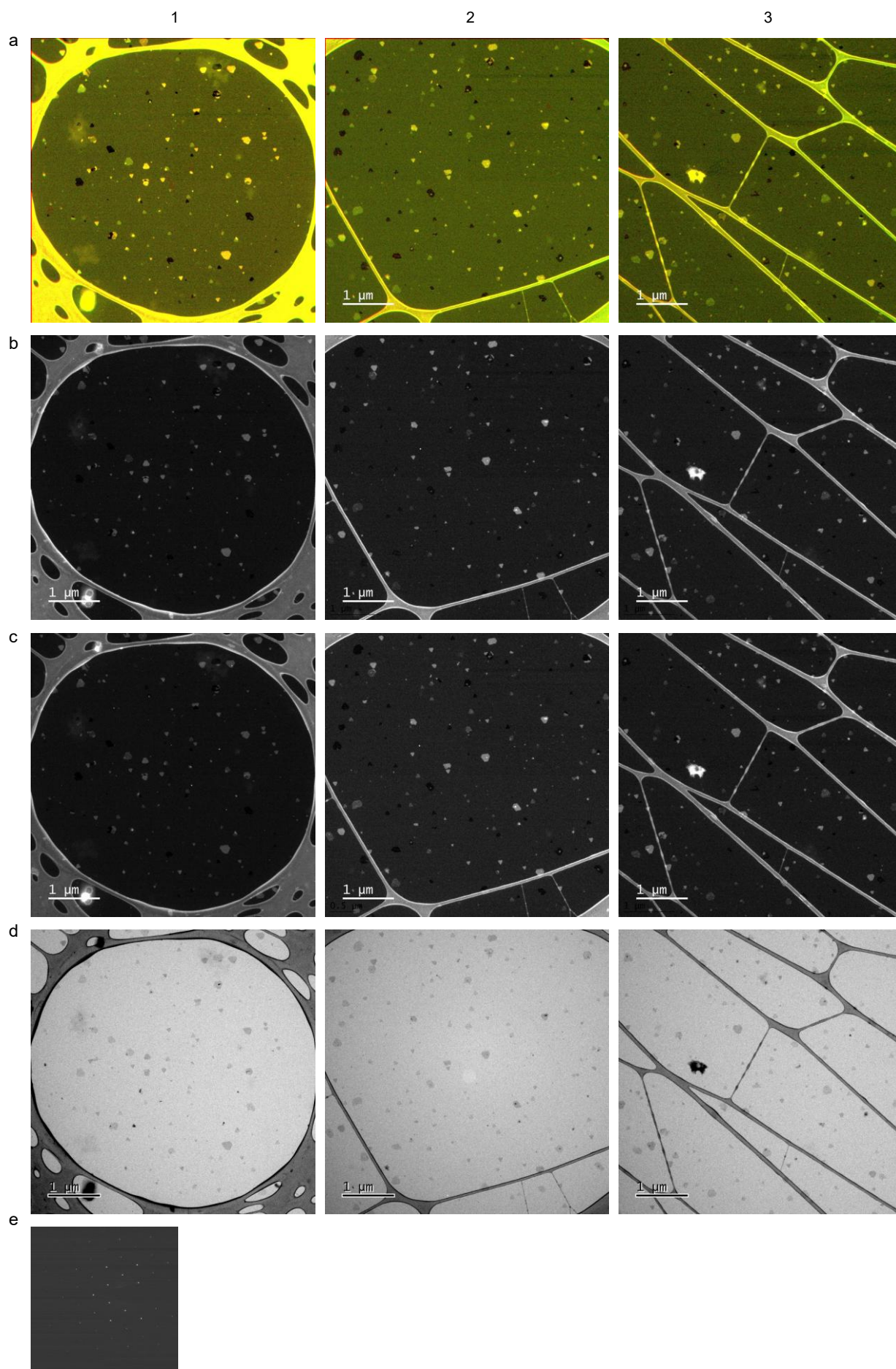
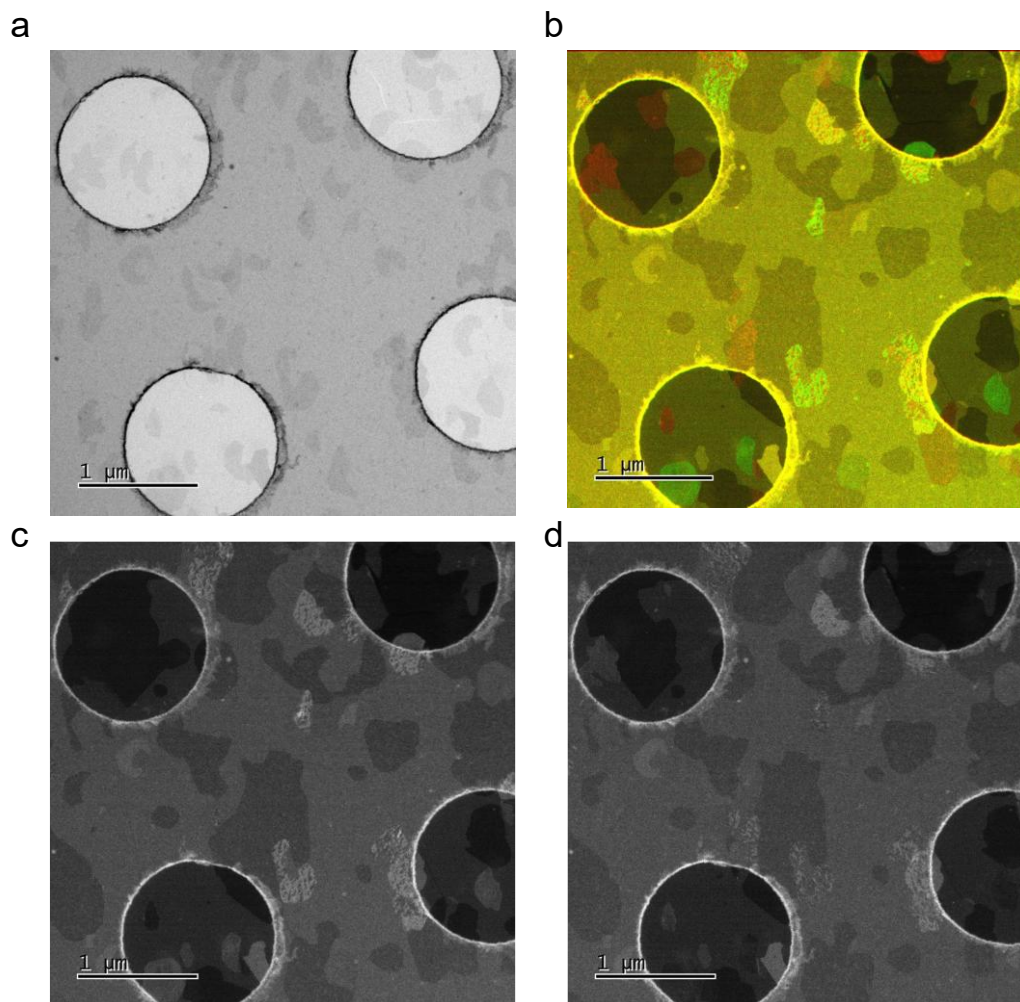


Figure S32. The TEM images from 3 regions for the MoS₂ monolayer deposited with 0.6 ppm of Mo(CO)₆ for 22 min, followed by 10 mins of the post-deposition annealing. The composite images with false colors (a) are composed using

310 the dark-field TEM images (b, c). The bright-field TEM images and a diffraction pattern are presented in (d) and (e),
 311 respectively. The composite image from region 2 was used in Figure 2b.



312
 313 **Figure S33.** The TEM images of the MoS₂ monolayer deposited with 1.0 ppm of Mo(CO)₆ for 11 min, followed by 10
 314 mins post-deposition annealing. A bright-field TEM image is shown in (a). A composite image with false colors (b) is
 315 composed using the dark-field TEM images (c, d). The dark, bright red and green areas on the composite images
 316 correspond to the misoriented domains. The misoriented domains can be distinguished from the secondary layer
 317 islands by comparing the composite and the bright-field image. Only secondary layer islands are visible on the bright-
 318 field image. The composite image was used in Figure 6a.

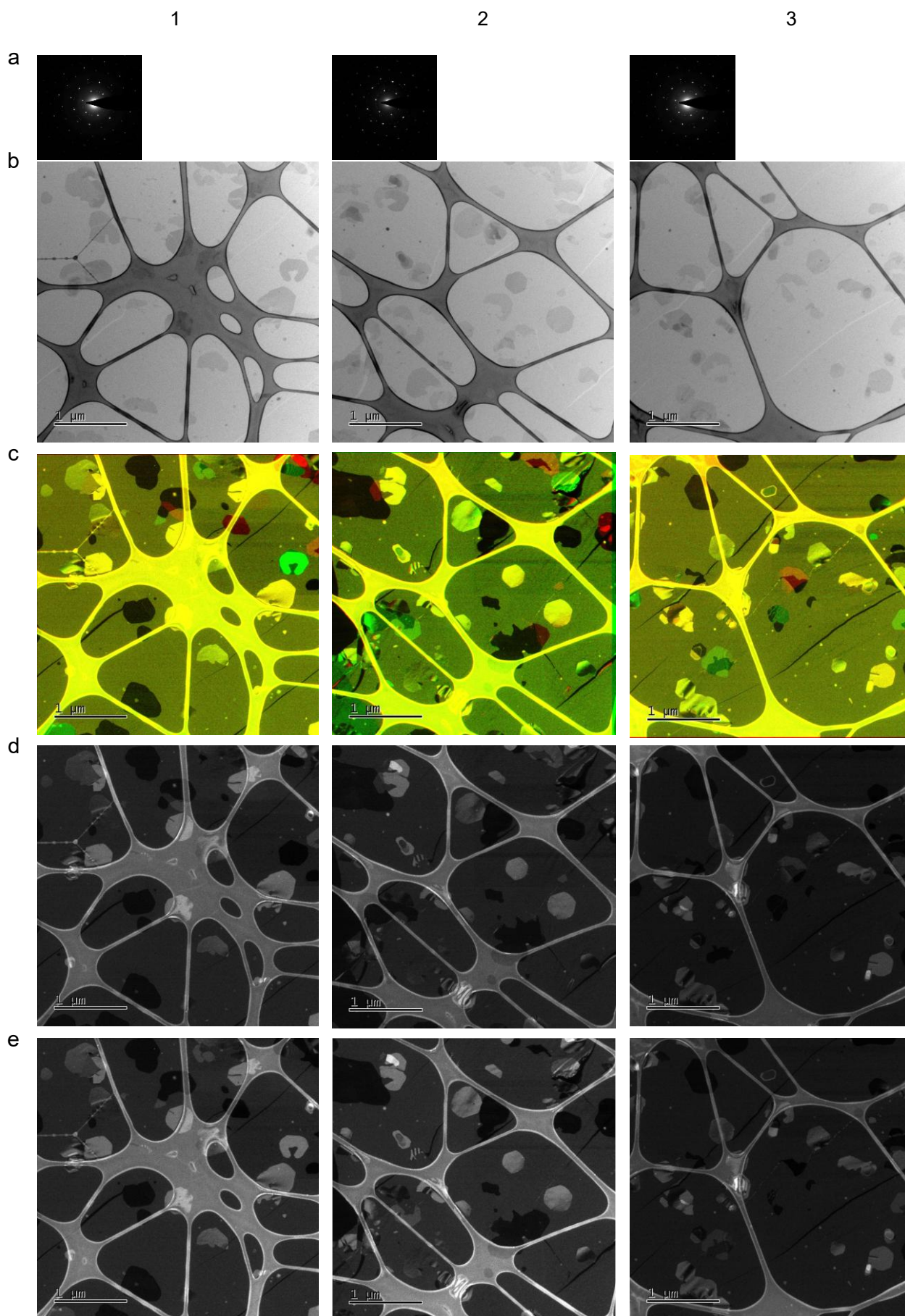
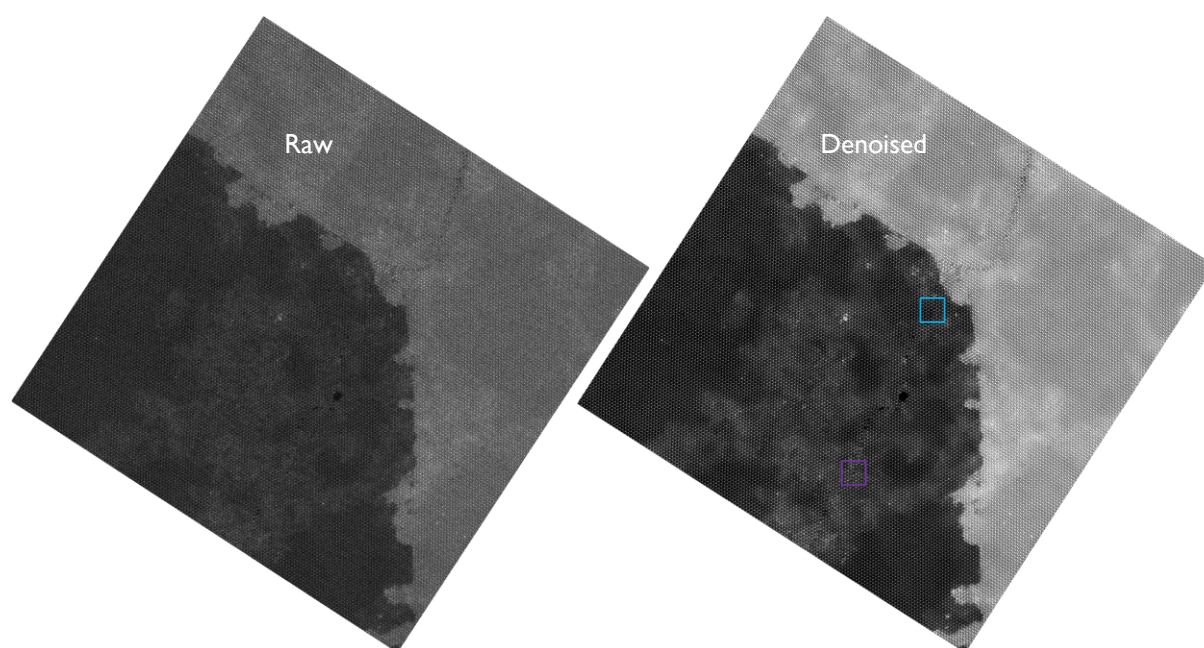


Figure S34. The TEM images from 3 regions for the MoS₂ monolayer deposited with 1.0 ppm of Mo(CO)₆ for 11 min, followed by 15 mins post-deposition annealing. The bright-field TEM images and the diffraction patterns are presented in (b) and (a), respectively. The composite images with false colors (c) are composed using the dark field

323 TEM images (d, e). The dark, bright red and green areas on the composite images correspond to the misoriented
 324 domains. The misoriented domains can be distinguished from the secondary layer islands by comparing the
 325 composite and the bright-field images. Only secondary layer islands are visible on the bright-field images. The
 326 composite image from region 1 was used in Figure 6b.



327
 328 **Figure S35.** Large area HR-STEM images used in Figure 3e. Raw image was denoised using using trained deep learning
 329 model.⁷ The blue square (top) highlights γ -grain boundary, the violet square (bottom) highlights β -grain boundary.

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